

The IAF mHEMT Low-Noise Technology and its Extension to Cryogenic Applications

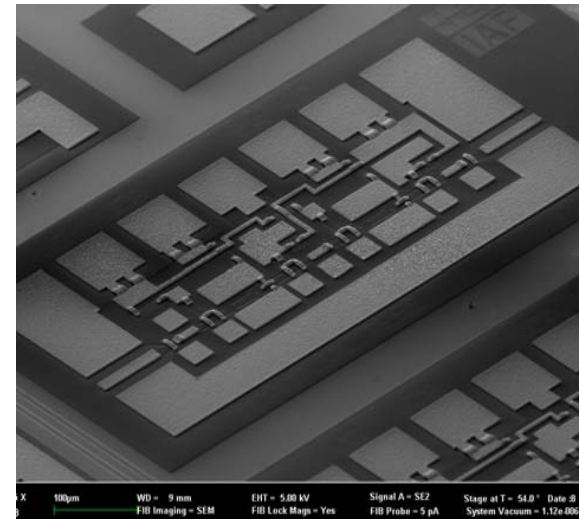
Matthias Seelmann-Eggebert, Arnulf Leuther, Hermann Maßler,
Beatriz Aja*, Daniel Bruch, Axel Tessmann, Ingmar Kallfass,
and Michael Schlechtweg

* On leave from University of Cantabria

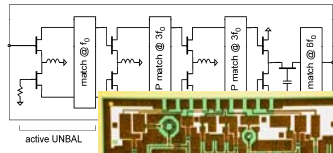
Fraunhofer Institut für Angewandte Festkörperphysik,
Tullastrasse 72, D-79108 Freiburg

Outline

- IAF Microwave Competences
- IAF mHEMT Technologies
- MMICs
- Noise Performance
- IAF SS mHEMT Model
- Extension of mHEMT Model
- Technology Improvements?
- Effect of Gate Leakage
- Summary

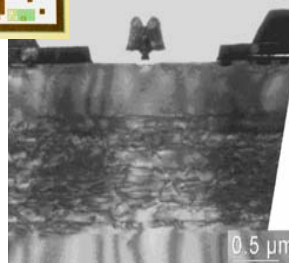
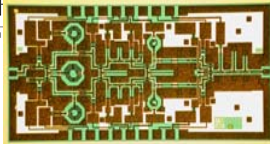


IAF Competences in Millimeterwave-Technology



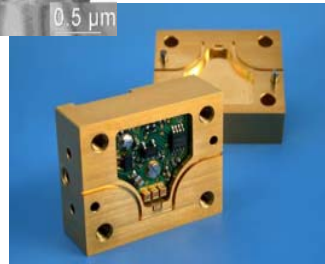
Circuit Design

Simulation
Modelling
Layout



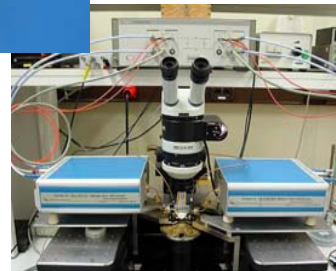
Technology

Epitaxy
MMIC Processing



Packaging

Module-Design und -manufacturing
Bonding, waveguide transitions
Hybride development



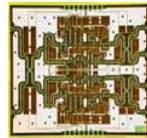
Charakterisation

S-Parameter up to 500 GHz
Power and Noise up to 210 GHz
Life-time measurements etc.

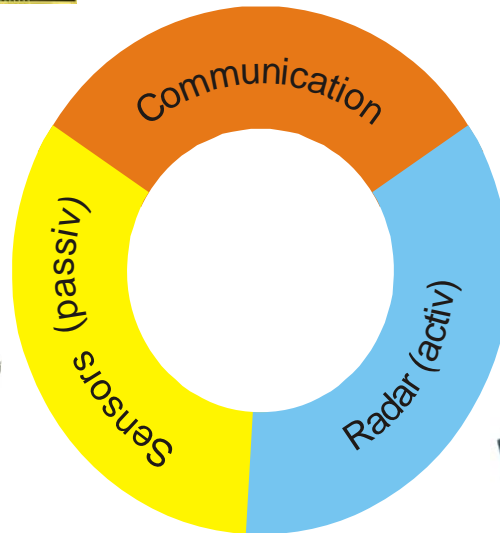
Fraunhofer
IAF



Cooperations in mm-Wave Technology



Sony
Wireless Communication at 60 GHz



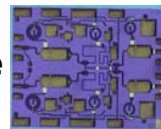
FGAN/FHR
Imaging Radar at 94 GHz



FGAN/FHR
Radiometers at 220 GHz



FGAN/FHR
SAR Radar at 94 and 220 GHz

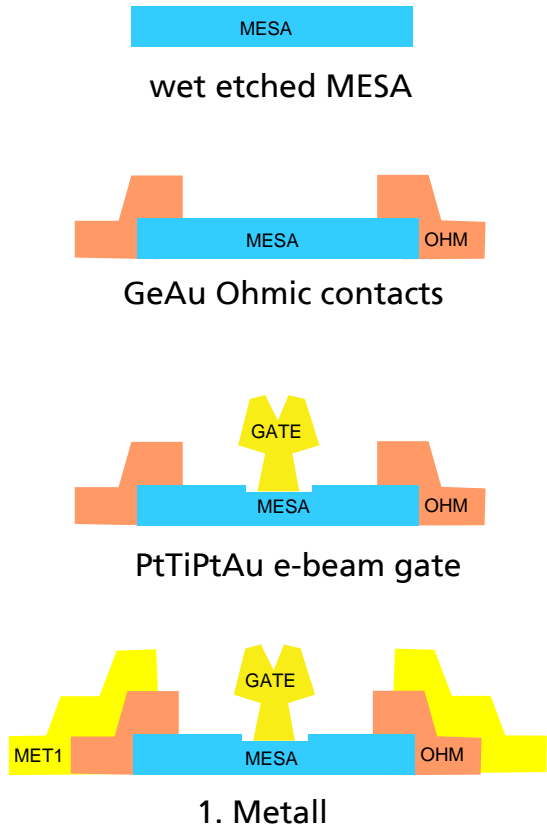


MPIfR/CAY/IRAM/SETI / Chalmers
UltraLow-Noise Amplifiers in cryo-operation

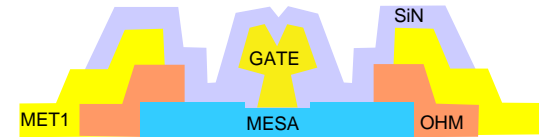


Radiometer Physics/ESA
Radiometry at 60/94/150/183/230 GHz

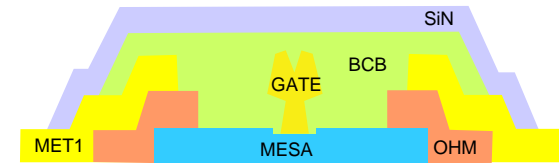
IAF mHEMT-Technology: Processing



100 nm technology



250 nm SiN passivation

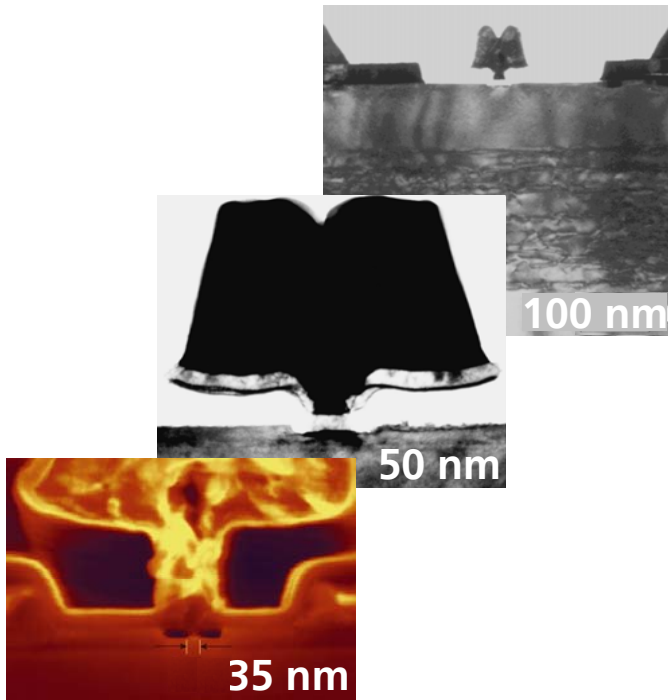


50/35 nm technology

250 nm SiN passivation on BCB

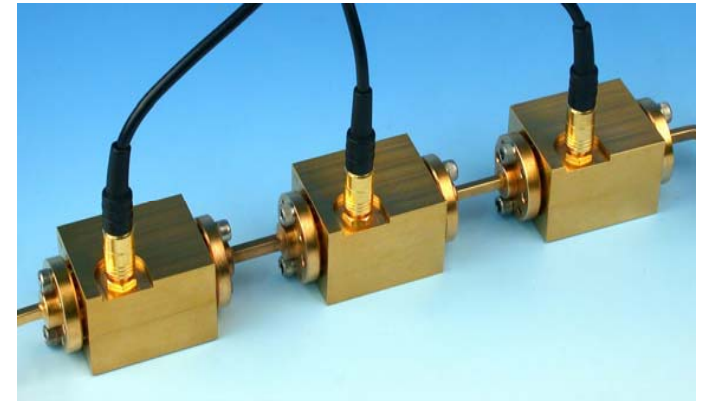
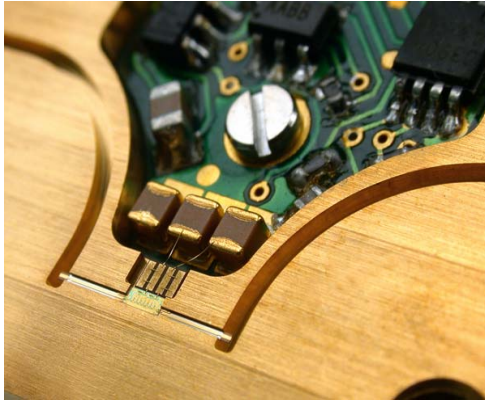
IAF m-HEMT Technology: Electrical Parameters

$\text{In}_x\text{Ga}_{1-x}\text{As}$ Channel /metamorphic buffer/ GaAs

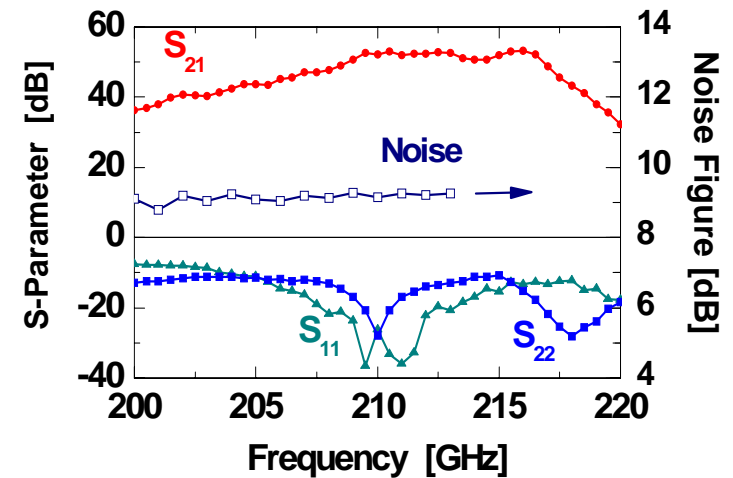


	35 nm	50 nm	100 nm
x (%)	80	80	65
R_C (Ωmm)	0.03	0.05	0.07
R_S (Ωmm)	0.10	0.15	0.23
R_g (Ω/mm)	250	250	400
$I_{D,\text{max}}$ (mA/mm)	1600	1200	900
V_{BD} (V)	1.5	2.5	4
$g_{m,\text{max}}$ (mS/mm)	2500	1800	1300
f_T (GHz)	550	380	220
f_{max} (GHz)	~700	~500	300

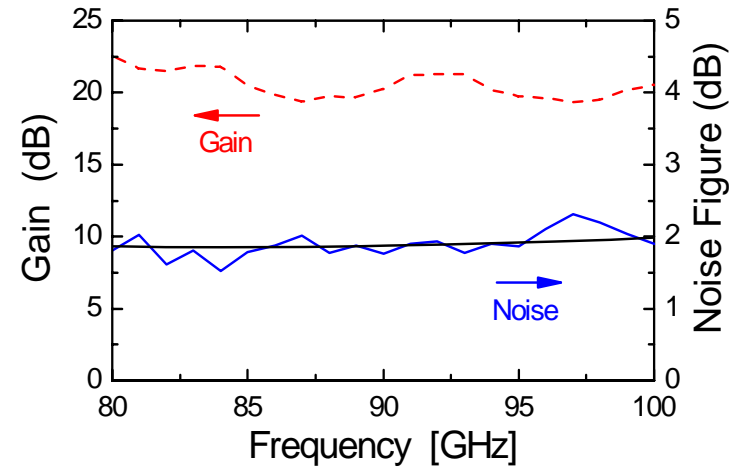
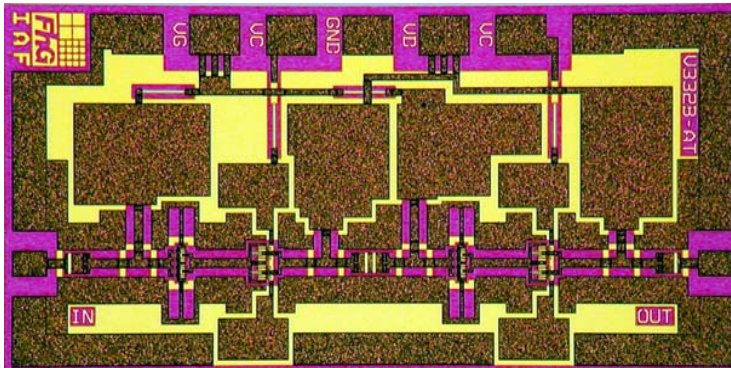
220 GHz Low-noise Amplifier Modules (2006)



- the first 220 GHz LNA modules
- gain (1 module): 18 dB
- gain (3 module): 53 dB
- noise: 9 dB @ 200..213 GHz



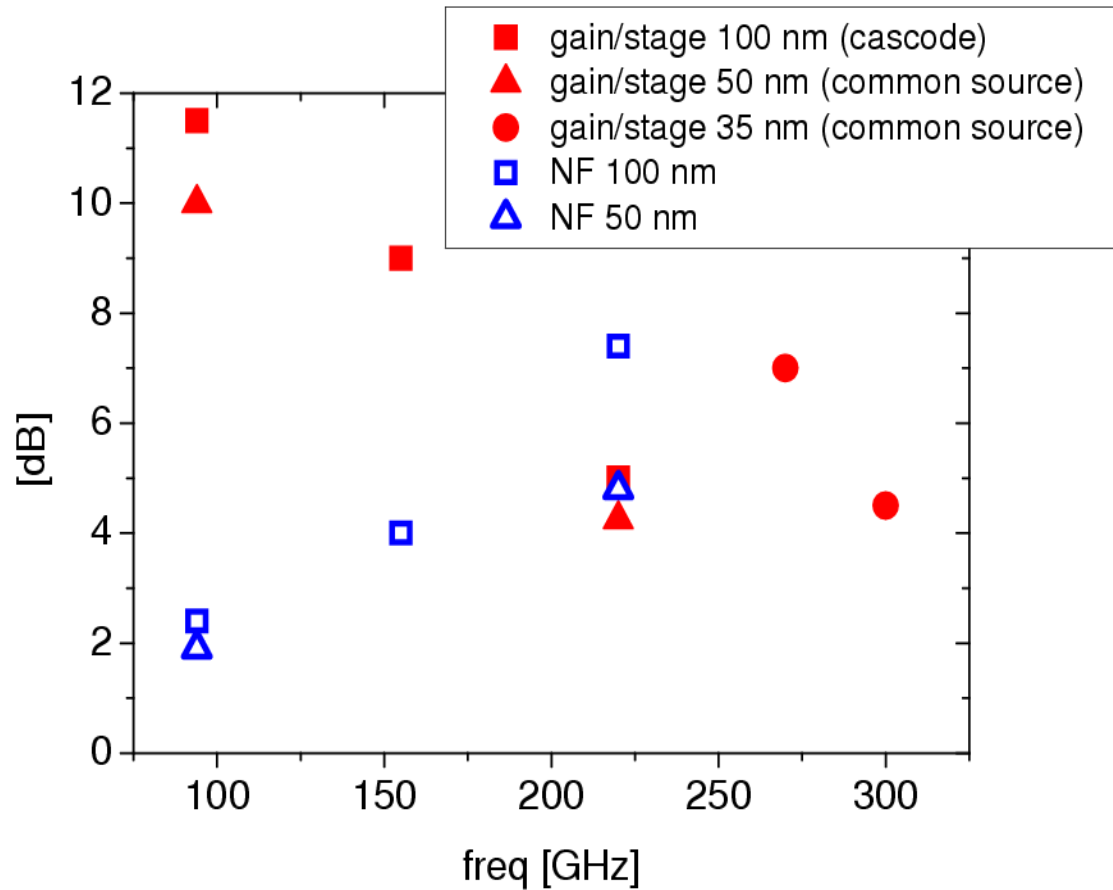
50 nm W-band Low-noise Amplifier



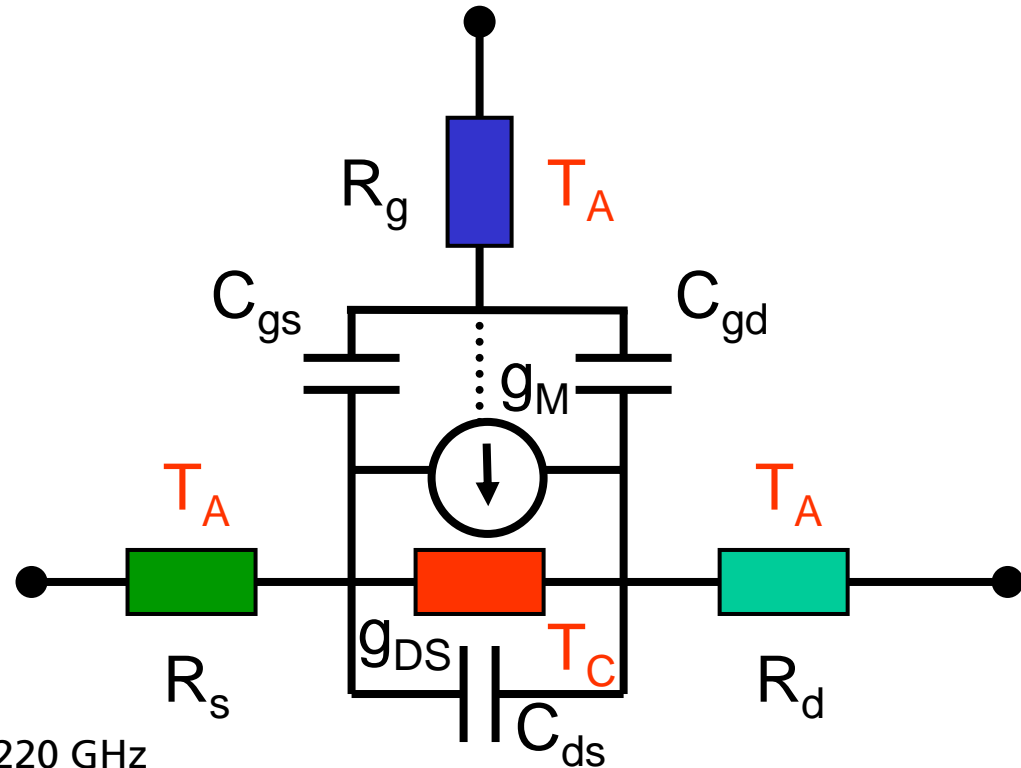
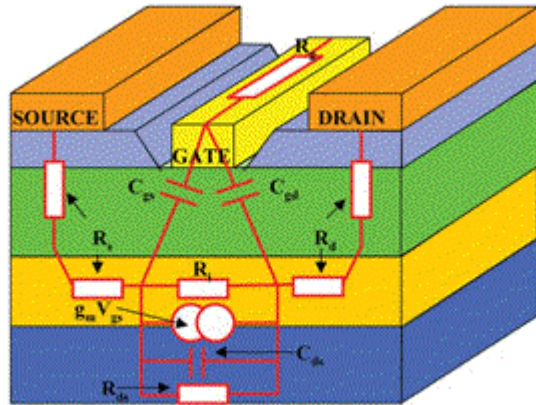
- two-stage cascode LNA
- grounded coplanar waveguide (GCPW)
- 50 nm gate length mHEMT
- 0.75 x 1.5 mm² chip size

- 20 dB gain (80 - 100 GHz)
- 1.9 dB noise figure

Small-Signal Amplifier Performance Summary



IAF Lumped Element mHEMT-Model



- ⇒ covers wide bias range
- ⇒ covers frequency range from 0.3 to 220 GHz
- ⇒ scalable from 10 μm to 120 μm
- ⇒ variable finger number
- ⇒ proper noise description
- ⇒ $T=300\text{ K}$

Extraction Tool LARA

The screenshot displays the LARA software interface with four graphs showing S-parameters versus frequency (GHz) from 0 to 100 GHz. The graphs are labeled Graph1, Graph2, Graph3, and Graph4.

- Graph1:** $S_{11}(S=\text{real}, B=\text{imag})$ vs. freq(GHz). The y-axis ranges from -0.5 to 0.5.
- Graph2:** $S_{12}(S=\text{real}, B=\text{imag})$ vs. freq(GHz). The y-axis ranges from -0.15 to 0.15.
- Graph3:** $S_{21}(S=\text{real}, B=\text{imag})$ vs. freq(GHz). The y-axis ranges from -8 to 6.
- Graph4:** $S_{22}(S=\text{real}, B=\text{imag})$ vs. freq(GHz). The y-axis ranges from -0.4 to 0.6.

The interface includes several control panels:

- Param:** Buttons for Load S2P, Load LSP, Load CITI, Load DIV, Save Model, and Vars.
- Set:** Buttons for S2P, S2P, S2P, and Test.
- Datasets:** Current Set: F2x60_c17_g1d1. Includes buttons for S, A, C, I, Delete, Select, and AP.
- Plot:** Buttons for P, C, E, S, A, M, W. Includes checkboxes for Autoscale, New Axes, and 3D.
- Model:** BiasAllnF_Nc1_TP_correctRbBest_N2, Modeltyp:0.
- Set Manager:** Table with columns Start, End, Step, and units.
- Plot-SS:** S-Parameter real/imag, checkboxes for DC, nS, W, and Common Parasitics.

Weights and Deviations panel:

S11	1	3.1110
S12	1	4.9456
S21	1	2.7385
S22	1	3.8020
MSGMAG	0	0
KFac	0	0

Buttons: OK, End.

LARA Model Scripts

Parameters

Bias 0

<input type="checkbox"/> Cgs_0	4.35E-4
<input type="checkbox"/> Rgs_0	0.00E0
<input type="checkbox"/> Cgd_0	2.08E-4
<input type="checkbox"/> Rgd_0	0.00E0
<input type="checkbox"/> Cds_0	1.78E-4
<input type="checkbox"/> gDS_0	4.45E-2
<input type="checkbox"/> gM_0	1.17E-1
<input type="checkbox"/> tauM_0	3.72E-4

Bias 1

<input type="checkbox"/> Cgs_1	6.83E-2
<input type="checkbox"/> Rgs_1	0.00E0
<input type="checkbox"/> Cgd_1	2.97E-1
<input type="checkbox"/> Rgd_1	0.00E0
<input type="checkbox"/> Cds_1	-1.90E-1
<input type="checkbox"/> gDS_1	2.88E0
<input type="checkbox"/> gM_1	-3.74E0
<input type="checkbox"/> tauM_1	0.00E0

Bias 2

<input type="checkbox"/> Cgs_2	4.95E-1
<input type="checkbox"/> Rgs_2	0.00E0
<input type="checkbox"/> Cgd_2	-1.21E-1
<input type="checkbox"/> Rgd_2	0.00E0
<input type="checkbox"/> Cds_2	1.27E-1
<input type="checkbox"/> gDS_2	1.55E0
<input type="checkbox"/> gM_2	8.73E0
<input type="checkbox"/> tauM_2	0.00E0

Bias 3

<input type="checkbox"/> Cgs_3	2.11E-3
<input type="checkbox"/> Rgs_3	0.00E0
<input type="checkbox"/> Cgd_3	1.21E0
<input type="checkbox"/> Rgd_3	0.00E0
<input type="checkbox"/> Cds_3	0.00E0
<input type="checkbox"/> gDS_3	5.89E0
<input type="checkbox"/> gM_3	-4.17E0
<input type="checkbox"/> tauM_3	0.00E0

Bias 4

<input type="checkbox"/> Cgs_4	-6.38E-2
<input type="checkbox"/> Rgs_4	0.00E0
<input type="checkbox"/> Cgd_4	1.58E-2
<input type="checkbox"/> Rgd_4	0.00E0
<input type="checkbox"/> Cds_4	0.00E0
<input type="checkbox"/> gDS_4	-2.31E-1
<input type="checkbox"/> gM_4	-1.13E0
<input type="checkbox"/> tauM_4	0.00E0

Bias 5

<input type="checkbox"/> Cgs_5	1.33E-1
<input type="checkbox"/> Rgs_5	0.00E0
<input type="checkbox"/> Cgd_5	-1.51E-1
<input type="checkbox"/> Rgd_5	0.00E0
<input type="checkbox"/> Cds_5	0.00E0
<input type="checkbox"/> gDS_5	-1.78E0
<input type="checkbox"/> gM_5	-3.17E-2
<input type="checkbox"/> tauM_5	0.00E0

Access

<input type="checkbox"/> rg	2.32E2
<input type="checkbox"/> rgc	0.00E0
<input type="checkbox"/> Rb	2.11E-1

Noise Temperatures

<input type="checkbox"/> T0	2.97E2
<input type="checkbox"/> Tgs	2.97E2
<input type="checkbox"/> Tg	2.97E2
<input type="checkbox"/> Td	2.97E2
<input type="checkbox"/> Ts	2.97E2
<input type="checkbox"/> Tds_0	1.26E3
<input type="checkbox"/> Tds_1	-2.72E0
<input type="checkbox"/> Tds_2	3.31E-1
<input type="checkbox"/> Tds_3	-4.36E0
<input type="checkbox"/> Tds_4	4.83E-2
<input type="checkbox"/> Tds_5	9.53E-1
<input type="checkbox"/> kTnF	-4.73E-2
<input type="checkbox"/> kTW	1.16E0

LCR Shell 2

<input type="checkbox"/> Cpgs_2	7.24E-6
<input type="checkbox"/> Cpgd_2	1.24E-6
<input type="checkbox"/> Cpds_2	8.54E-6
<input type="checkbox"/> Lg_2	1.29E-1
<input type="checkbox"/> Ld_2	9.97E-2
<input type="checkbox"/> Ls_2	6.63E-6

LCR Shell 4

<input type="checkbox"/> Cpgs_4	9.78E-6
<input type="checkbox"/> Cpgd_4	2.18E-6
<input type="checkbox"/> Cpds_4	8.49E-6
<input type="checkbox"/> Lg_4	3.92E-2
<input type="checkbox"/> Ld_4	5.28E-2
<input type="checkbox"/> Ls_4	2.01E-3

Port XT

<input type="checkbox"/> ZLin	5.00E1
<input type="checkbox"/> A0in	0.00E0
<input type="checkbox"/> ZLout	5.00E1
<input type="checkbox"/> A0out	0.00E0
<input type="checkbox"/> Fdep	6.30E-1
<input type="checkbox"/> tauIn_4	1.45E0
<input type="checkbox"/> tauOut_4	1.45E0
<input type="checkbox"/> tauIn_2	1.45E0
<input type="checkbox"/> tauOut_2	1.45E0

Geometry

<input type="checkbox"/> Vd0	1.00E0
<input type="checkbox"/> id0	1.00E-1
<input type="checkbox"/> rth	0.00E0
<input type="checkbox"/> pth	0.00E0

Weight

<input type="checkbox"/> lowfreq	0.00E0
<input type="checkbox"/> highfreq	3.00E1
<input type="checkbox"/> fridecay	3.33E-2
<input type="checkbox"/> frcenter	4.50E1
<input type="checkbox"/> frwidpar	0.00E0

Dev: 3.7447 fitting sets 1 to 12

OK Wght
Top P
dev T
Fit S
 A

parameter field

BiasAllnF_Nc1_TP_correctRbBest_N2.mps - Editor

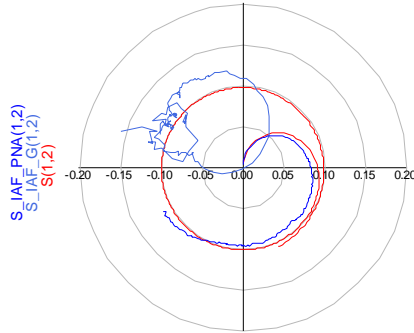
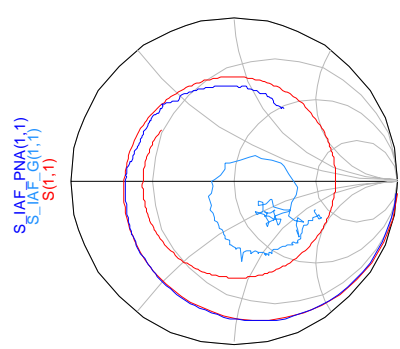
```
! END
Lg_2=1.29E-1
Ld_2=9.97E-2
Ls_2=6.63E-6
! VAR LCR_Shell_4
Cpgs_4=9.78E-6
Cpgd_4=2.18E-6
Cpds_4=8.49E-6
Lg_4=3.92E-2
Ld_4=5.28E-2
Ls_4=2.01E-3
! END
! VAR Port_XT
ZLin=5.00E+1
A0in=0.00E+0
ZLout=5.00E+1
A0out=0.00E+0
Fdep=6.30E-1
tauIn_4=1.45E+0
tauOut_4=1.45E+0
tauIn_2=1.45E+0
tauOut_2=1.45E+0
! END
! VAR Geometry
vdo=1.00E+0
ido=1.00E-1
rth=0.00E+0
pth=0.00E+0
! END
! VAR Weight
lowfreq=0.00E+0
highfreq=3.00E+1
fridecay=3.33E-2
frcenter=4.50E+1
frwidpar=0.00E+0
! END
! BLOCK Parasitics
R=rg*wtot/nFA2+rgc/nF
omega=2*pi*f+freq
y1=omega*(delta(nf-2)*Cpgs_2+delta(nf-4)*Cpgs_4)
y2=omega*(delta(nf-2)*Cpds_2+delta(nf-4)*Cpds_4)
y3=omega*(delta(nf-2)*Cpgd_2+delta(nf-4)*Cpgd_4)
z1=Rg_j*omega*(delta(nf-2)*Lg_2+delta(nf-4)*Lg_4)*wtot
z2=Rb/wtot+j*omega*(delta(nf-2)*Ld_2+delta(nf-4)*Ld_4)*wtot
z3=Rb/wtot+j*omega*(delta(nf-2)*Ls_2+delta(nf-4)*Ls_4)*wtot
Len=300*(delta(nf-2)*tauOut_2+delta(nf-4)*tauOut_4)
AM1=A4T(21,2,2,3)
AM2=A4P(1,y1,y2,y3)
AM3=A4Bra(freq,Len1,ZLin,1,A0in,Fdep,0)
AM4=A4Ket(freq,Len2,ZLout,1,A0out,Fdep,0)
AM4PS=AM4*AM3*AM2*AM1
! END
! BLOCK Intrinsiccs
vds=(VDS-vd0)/vdo
ido=id0*wtot
TdFac=(1+kTW*wtot)/(1+kTnF*(nf-2))
TdsTds_0=(1+Tds_1*vds+Tds_2*ido+Tds_3*vdsA2+Tds_4*idoA2+Tds_5*vds*ido)
Cgs=Cgs_0*(1+Cgs_1*vds+Cgs_2*ido+Cgs_3*vdsA2+Cgs_4*idoA2+Cgs_5*vds*ido)
Cgd=Cgd_0*(1+Cgd_1*vds+Cgd_2*ido+Cgd_3*vdsA2+Cgd_4*idoA2+Cgd_5*vds*ido)
Cds=Cds_0*(1+Cds_1*vds+Cds_2*ido+Cds_3*vdsA2+Cds_4*idoA2+Cds_5*vds*ido)
gM=gM_0*(1+gM_1*vds+gM_2*ido+gM_3*vdsA2+gM_4*idoA2+gM_5*vds*ido)
gDS=gDS_0*(1+gDS_1*vds+gDS_2*ido+gDS_3*vdsA2+gDS_4*idoA2+gDS_5*vds*ido)
tauM=tauM_0*(1+tauM_1*vds+tauM_2*ido+tauM_3*vdsA2+tauM_4*idoA2+tauM_5*vds*ido)
Rgs=Rgs_0*(1+Rgs_1*vds+Rgs_2*ido+Rgs_3*vdsA2+Rgs_4*idoA2+Rgs_5*vds*ido)
Rgd=Rgd_0*(1+Rgd_1*vds+Rgd_2*ido+Rgd_3*vdsA2+Rgd_4*idoA2+Rgd_5*vds*ido)
yGS=j*omega*Cgs/(1+j*omega*Rgs*Cgs)
yGD=j*omega*Cgd/(1+j*omega*Rgd*Cgd)
yGM=(gM/(1+j*omega*Rgs*Cgs))/(1+j*omega*tauM)
yGS=yGS+j*omega*Cds
Yin=(wtot*Y0)*C22*FV((yGS+yGD),(-yGD),(yGM-yGS),(YDS+yGS))
Y=EmbedY(AM4PS,Yin)
! END
! BLOCK NOISE_DEF
UGSN=sqrt((Rgs/wtot)*Tgs)+j*0
IDSN=sqrt((gDS*wtot)*Tds*TdsFac)+j*0
URGN=sqrt((Rg*Tg)+j*0)
URDN=sqrt((Rb/wtot)*Td)+j*0
URSN=sqrt((Rb/wtot)*Ts)+j*0
IQXN=sqrt(T0)+j*0
! END
! BLOCK NOISE_GENERATOR
I11N=(yGS*wtot)*UGSN
I21N=(yGM*wtot)*UGSN+IDSN
I1V=CVec2(I11N,I21N)
Z1=InvC2X2(Y1N)
Y=EmbedY(AM1,Yin)
UPV=CVec2((URGN+URSN),(URDN+URSN))
IPN=YR*((I1/50)*UPV+(Z1*I1V))
APRES=AM4*AM3*AM2
M1N=M1Embed(A4rest,Yr)
IXN=M1N*IXN
! END
```

Script file
parameter definition block

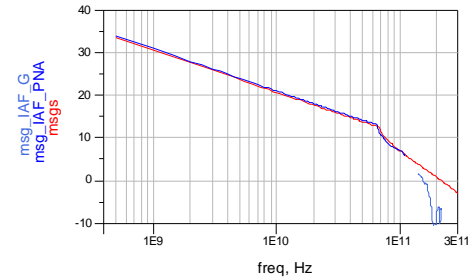
model equations

ADS Model Verification

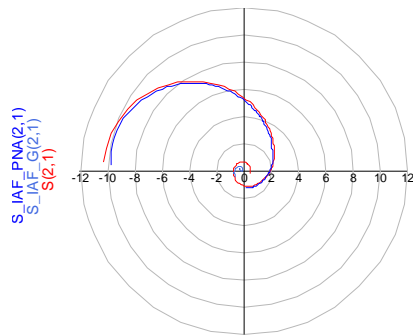
F2x60 id=400 Vd=1 LG=100



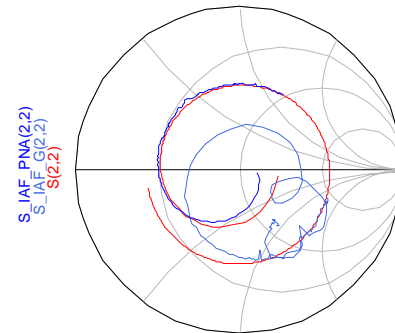
freq (500.0MHz to 300.0GHz)
freq (140.0GHz to 220.0GHz)
freq (500.0MHz to 110.0GHz)



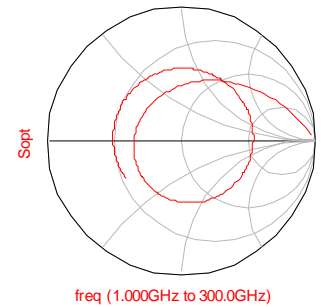
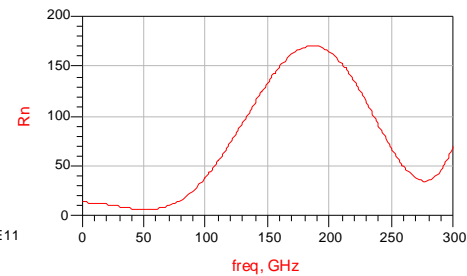
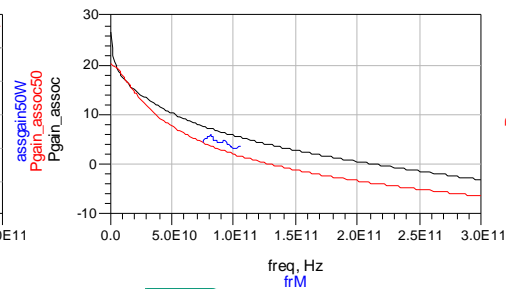
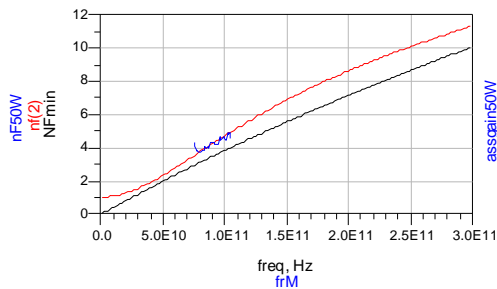
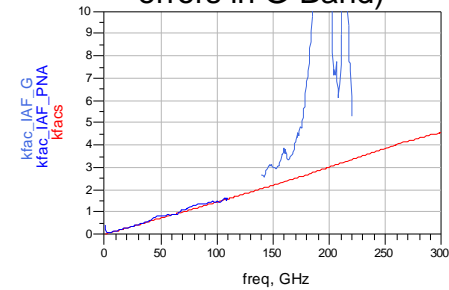
On-wafer probing
(Large Systematic measurement errors in G-Band)



freq (500.0MHz to 300.0GHz)
freq (140.0GHz to 220.0GHz)
freq (500.0MHz to 110.0GHz)

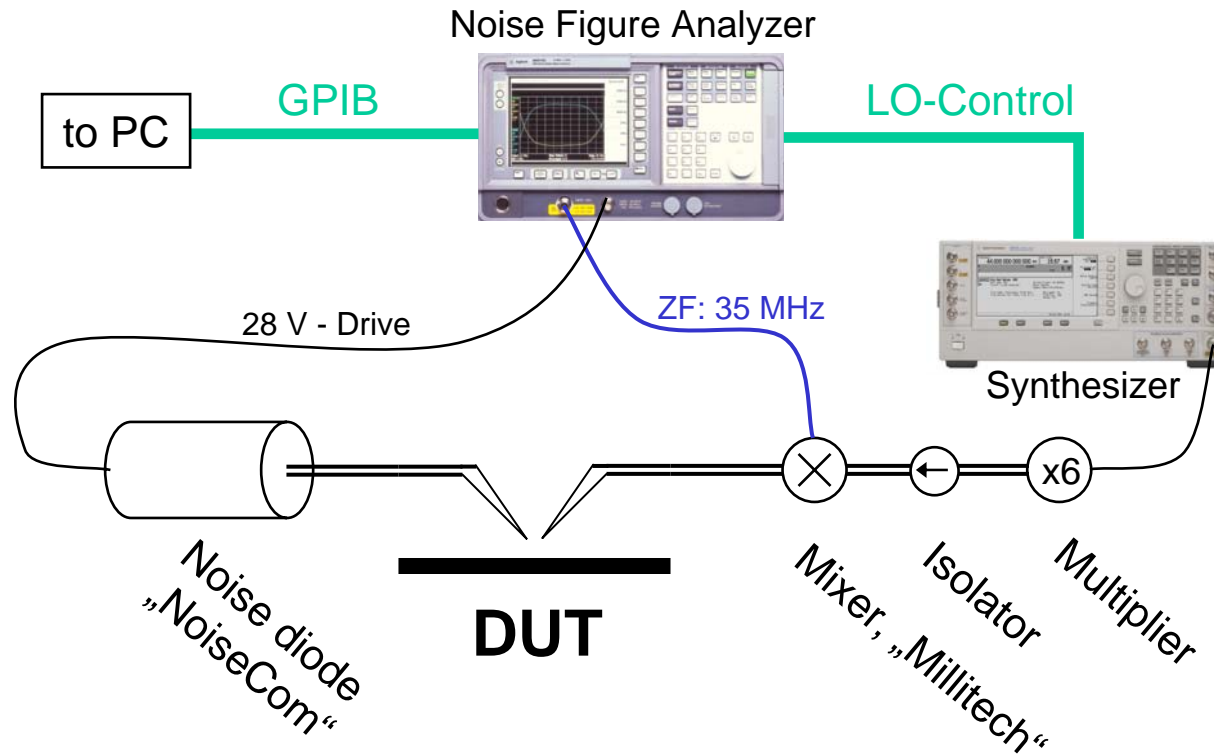


freq (500.0MHz to 300.0GHz)
freq (140.0GHz to 220.0GHz)
freq (500.0MHz to 110.0GHz)

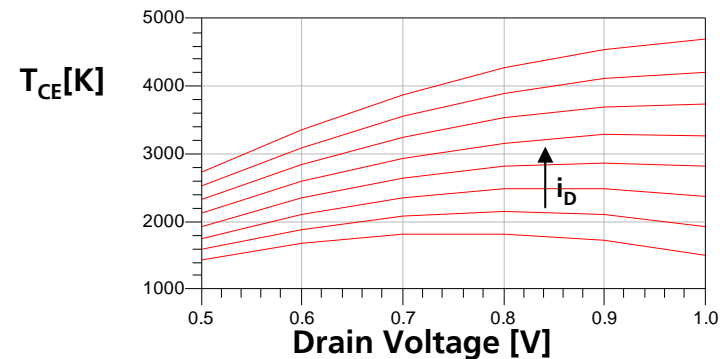
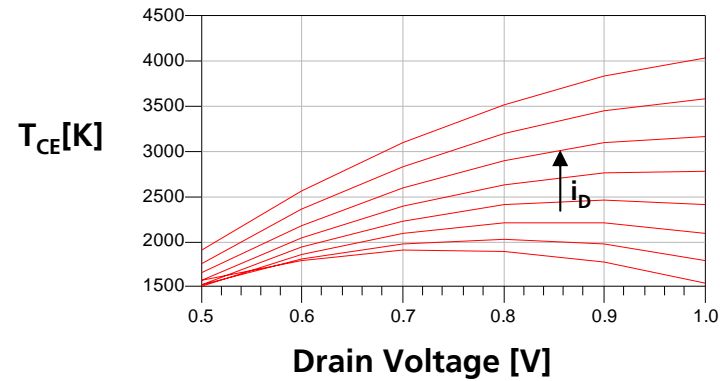
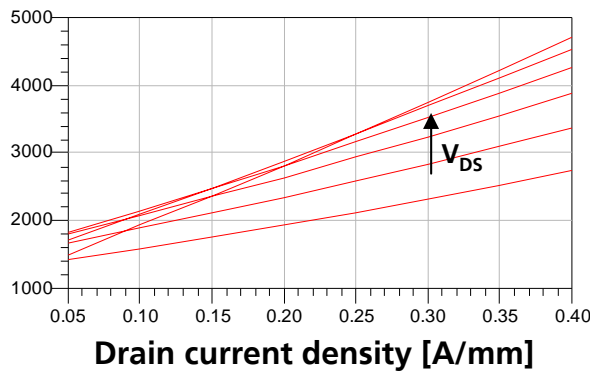
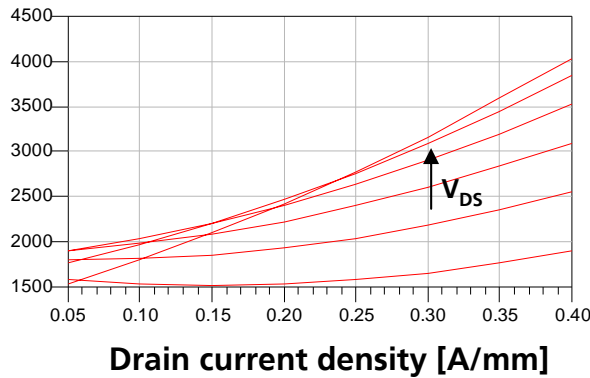


freq (1.000GHz to 300.0GHz)

NF50 Measurement at W-Band



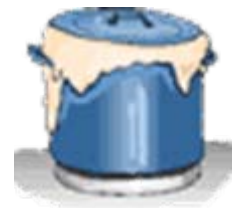
Electron Temperature vs Bias (T=300K)



IAF mHEMT

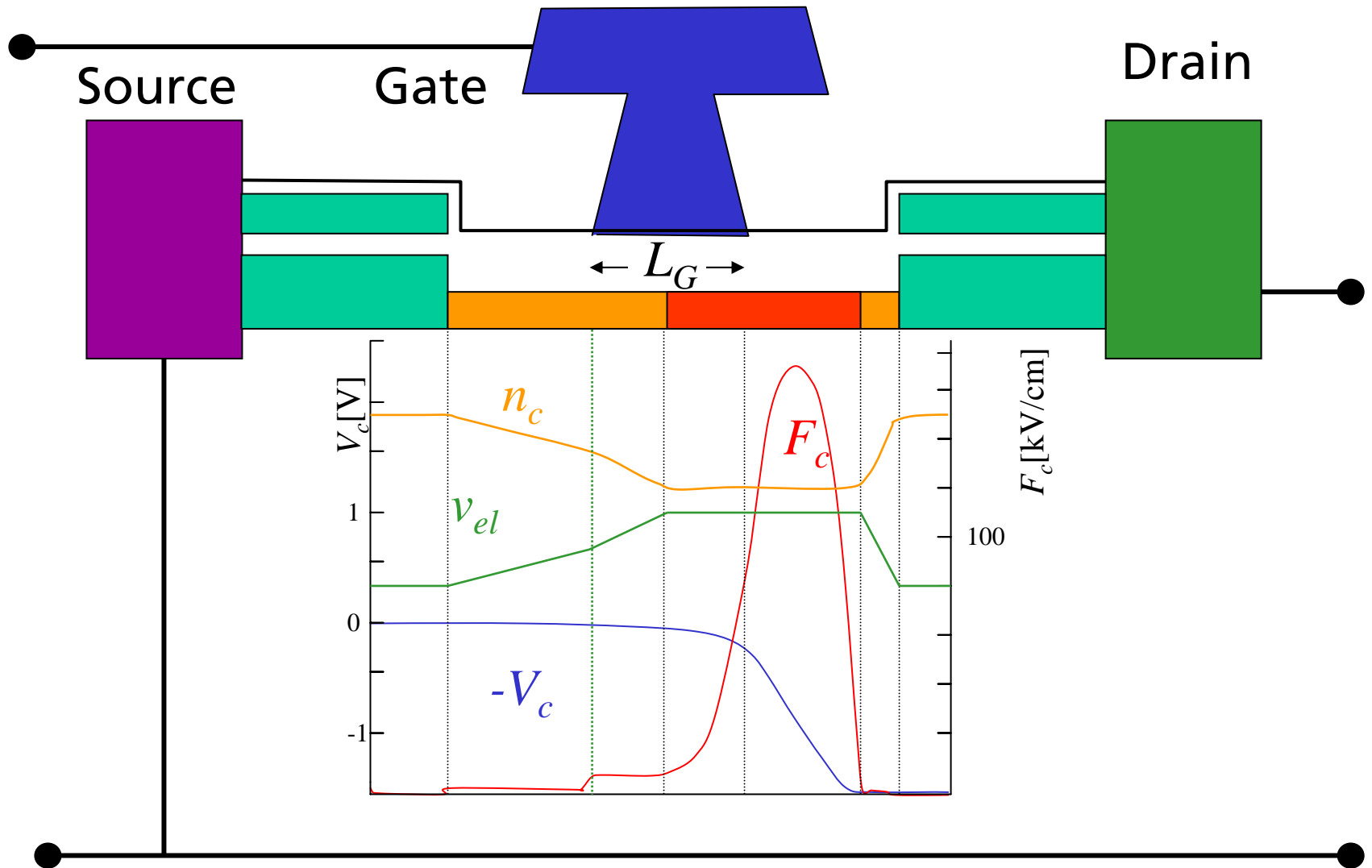
$L_G=100$ nm

$L_G=50$ nm

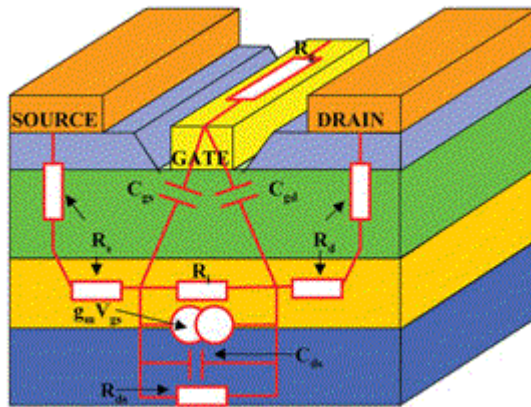


Hot electrons in high field region of transistor

Short Channel HEMT

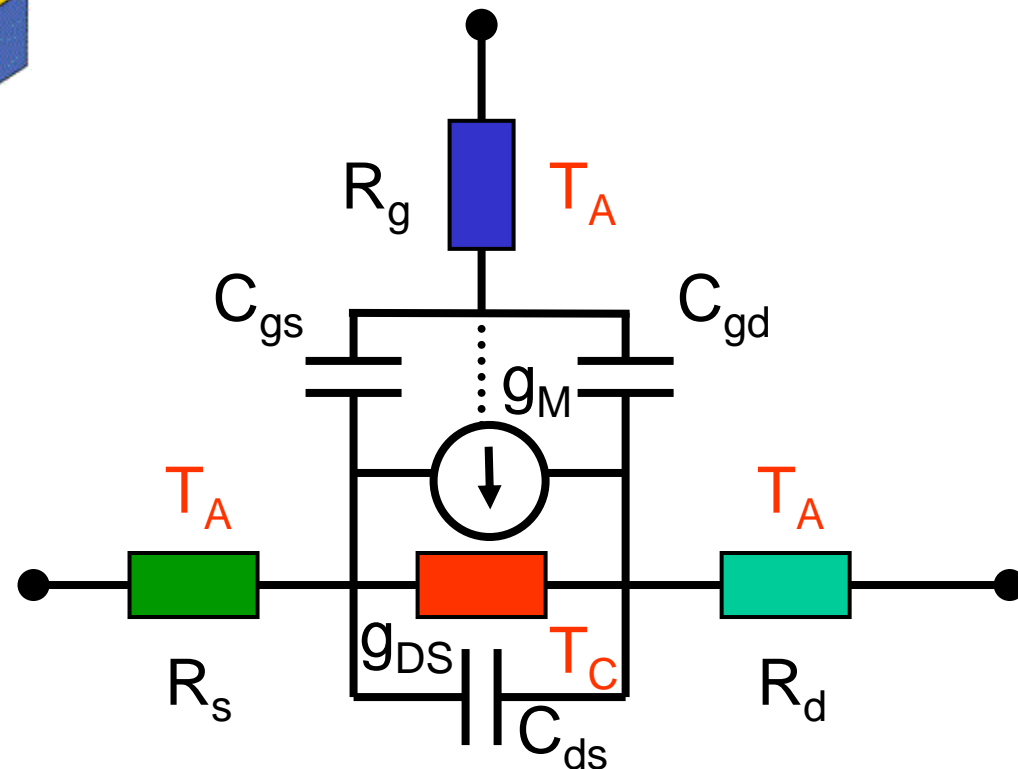


Lumped Element mHEMT-Model and Low Noise Technology Criteria



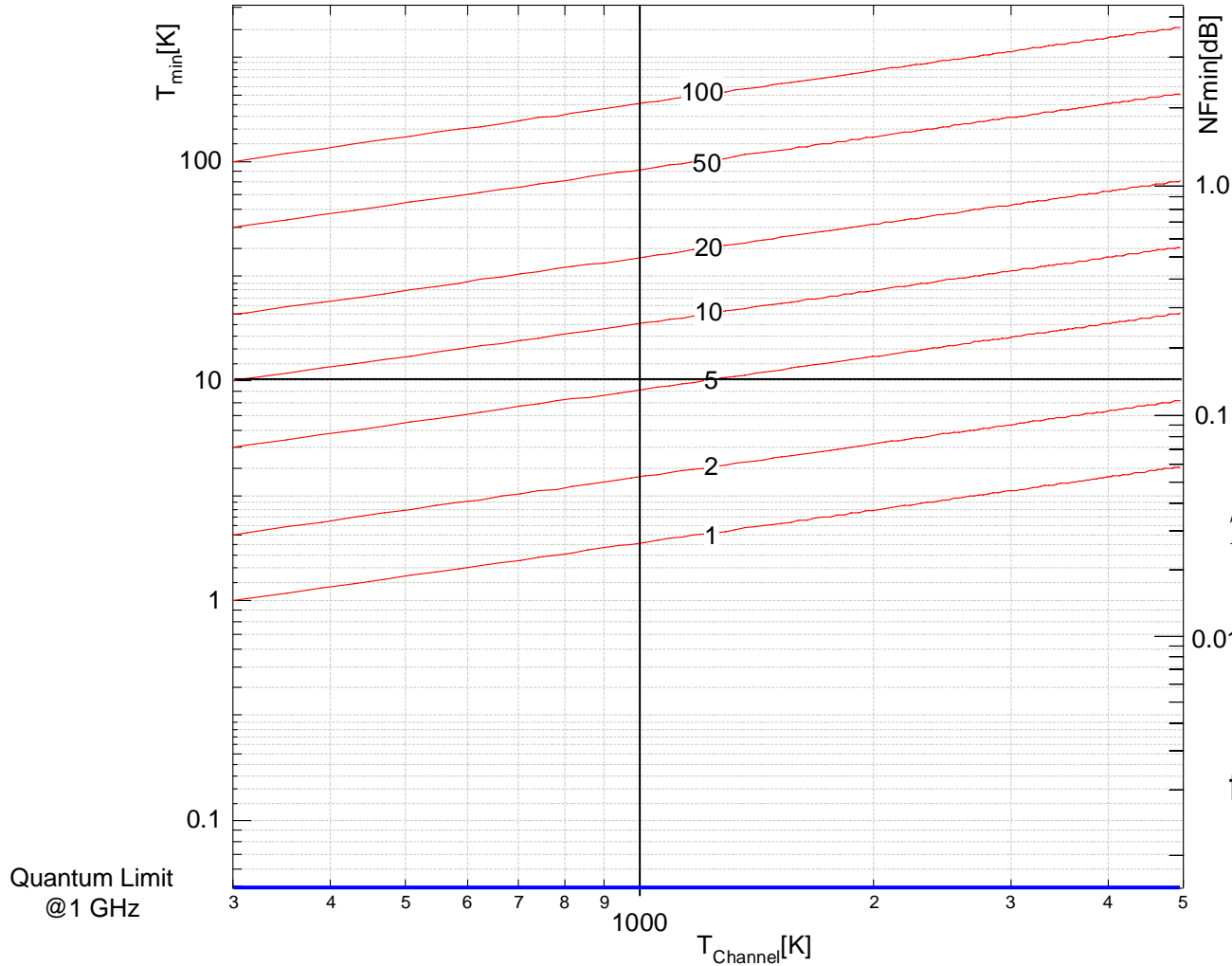
Technological Low Noise Criteria

- ⇒ high electron mobility (g_{DS} , g_M)
- ⇒ low sheet resistance (R_s, R_d)
- ⇒ low contact resistance (R_s, R_d)
- ⇒ low gate line resistance (R_g)
- ⇒ **High Gain** (small channel distance)
- ⇒ **Temperature??**



$$T_{\min} = \sqrt{T_{\text{Ambient}} T_{\text{Channel}} f / f_{\max}}$$

Assessment of Minimum Noise Temperature for mHEMT

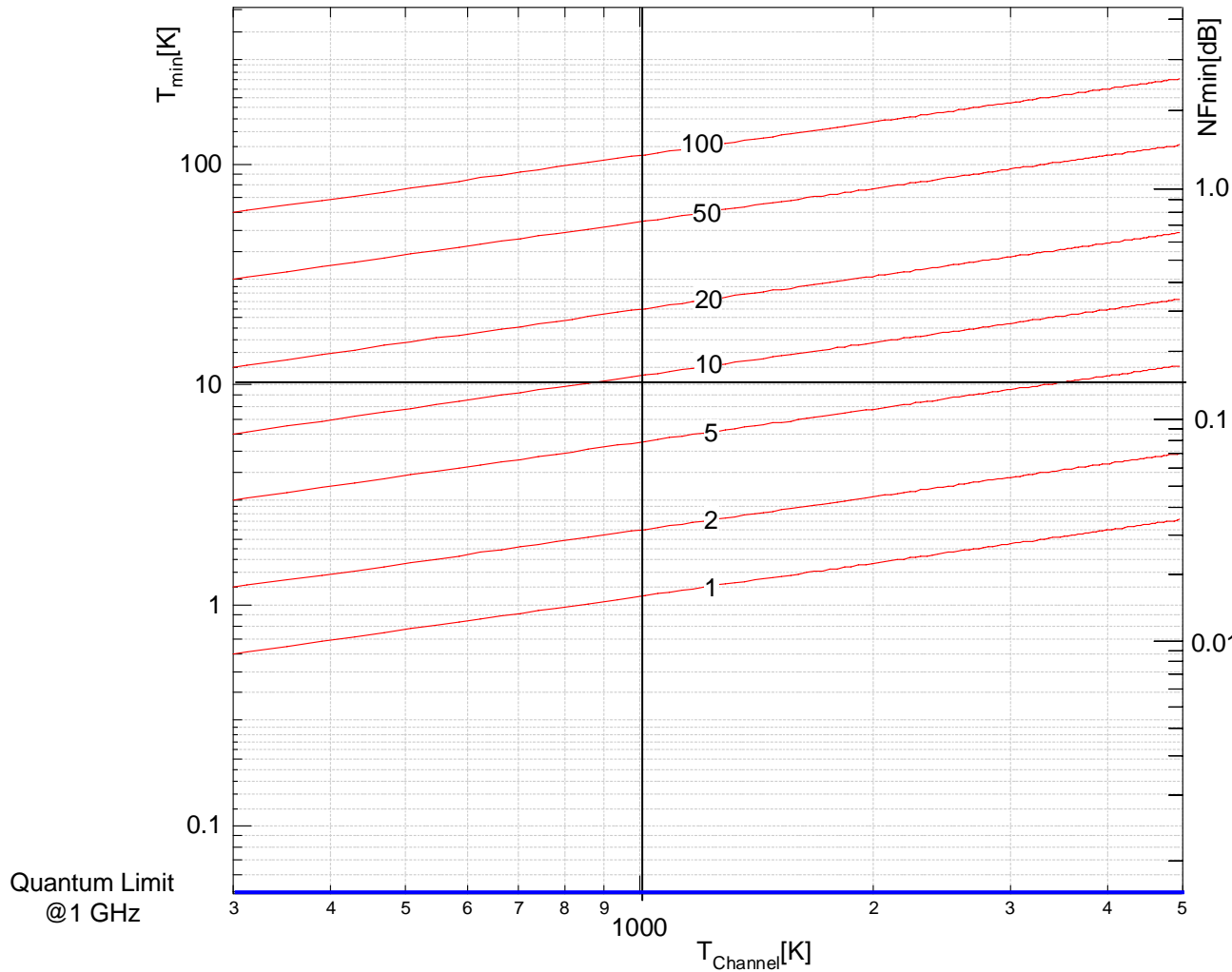


$L_G = 100 \text{ nm}$
 $f_{\max} = 300 \text{ GHz}$
 $T_{\text{amb}} = 300 \text{ K}$

$$T_{\min} = \sqrt{T_{\text{Ambient}} T_{\text{Channel}} f / f_{\max}}$$

for $f \ll f_{\max}$

Assessment of Minimum Noise Temperature for mHEMT

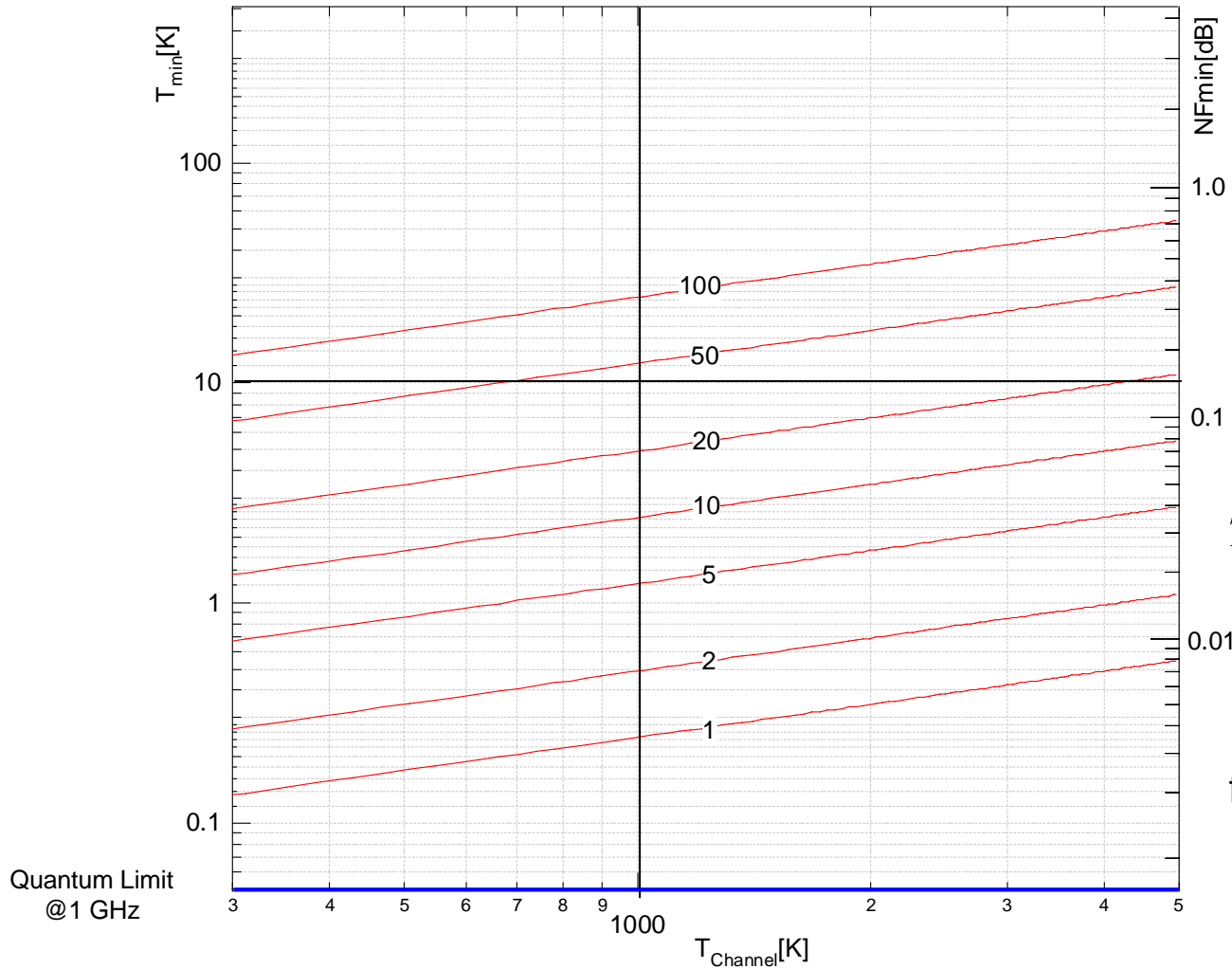


$L_G = 50 \text{ nm}$
 $f_{\max} = 500 \text{ GHz}$
 $T_{\text{amb}} = 300 \text{ K}$

$$T_{\min} = \sqrt{T_{\text{Ambient}} T_{\text{Channel}} f / f_{\max}}$$

for $f \ll f_{\max}$

Assessment of Minimum Noise Temperature for mHEMT

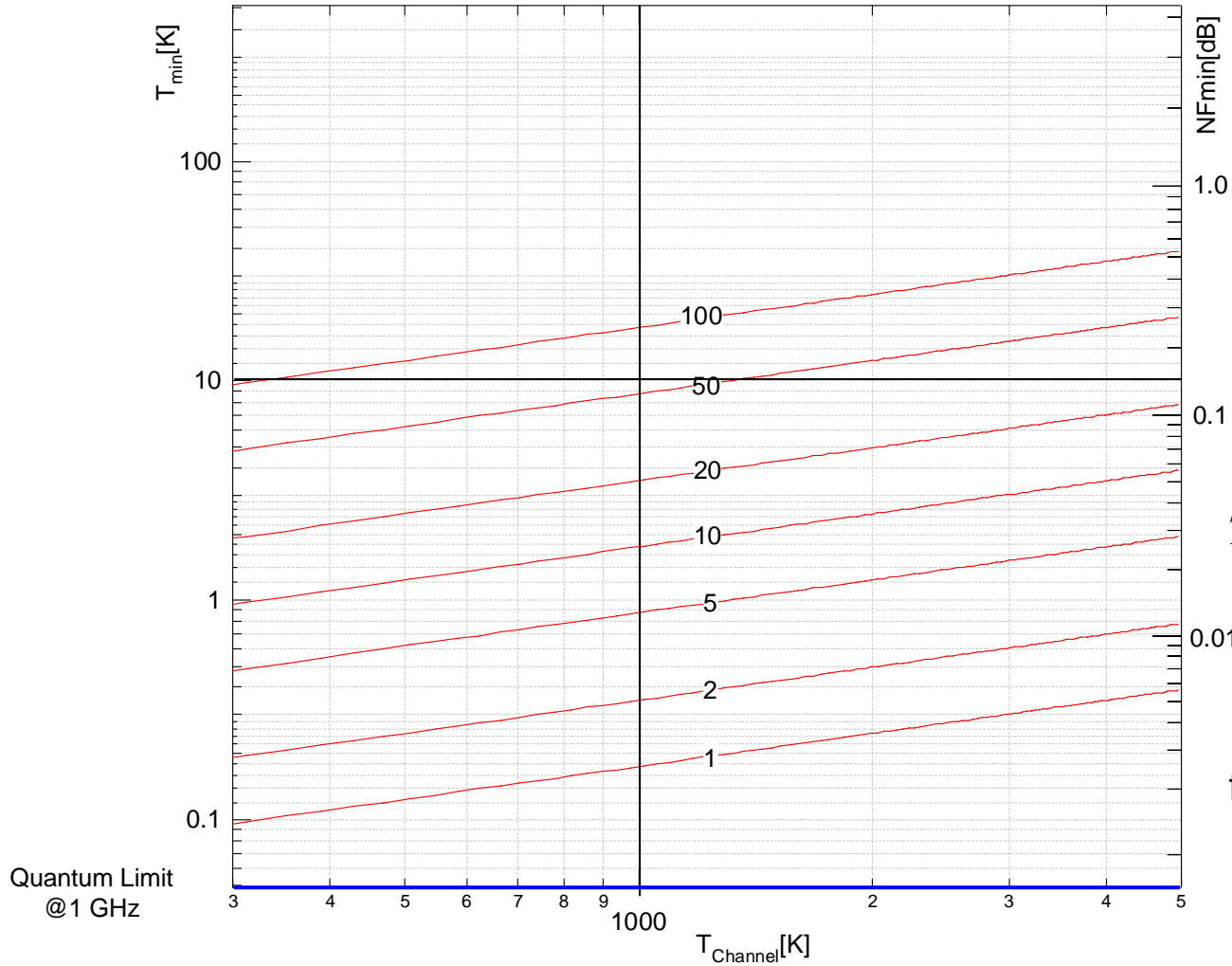


$L_G = 50 \text{ nm}$
 $f_{\max} = 500 \text{ GHz}$
 $T_{\text{amb}} = 15 \text{ K}$

$$T_{\min} = \sqrt{T_{\text{Ambient}} T_{\text{Channel}} f / f_{\max}}$$

for $f \ll f_{\max}$

Assessment of Minimum Noise Temperature for mHEMT

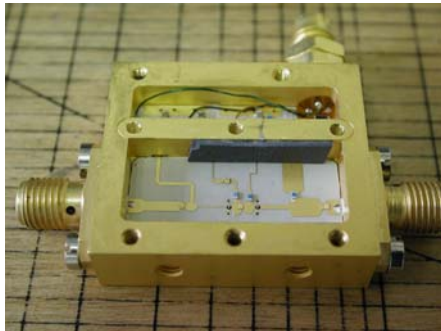
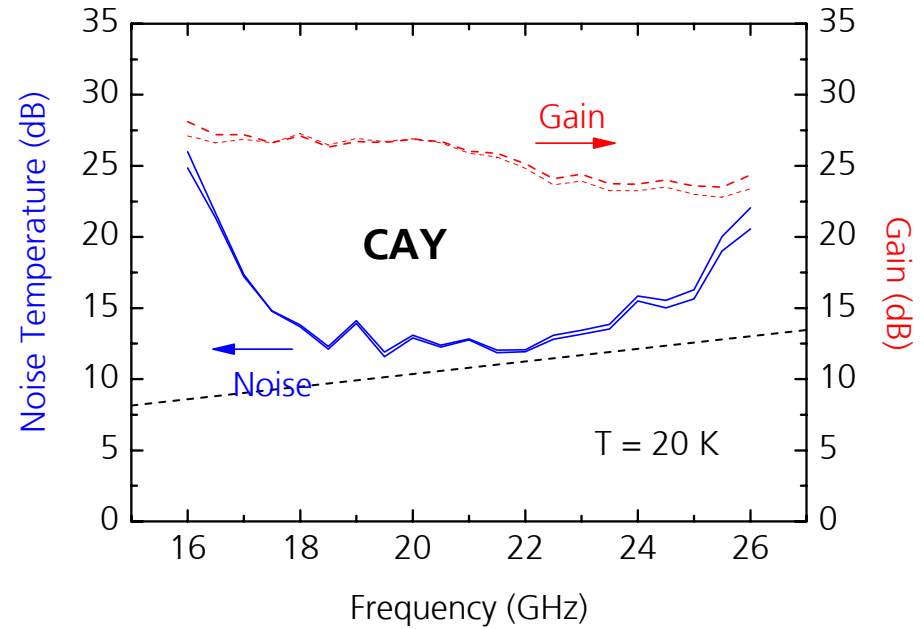
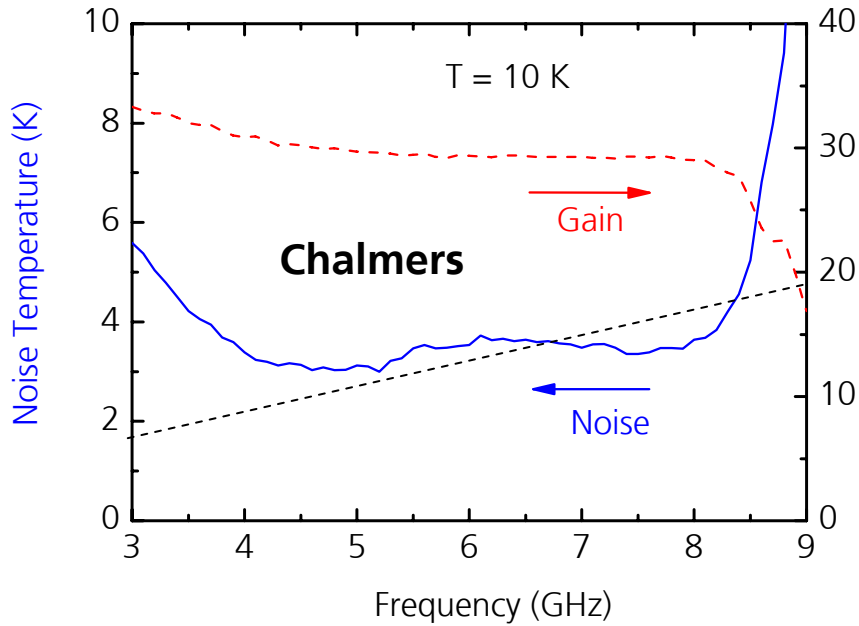


$L_G = 35$ nm
 $f_{\max} = 700$ GHz
 $T_{\text{amb}} = 15$ K

$$T_{\min} = \sqrt{T_{\text{Ambient}} T_{\text{Channel}} f / f_{\max}}$$

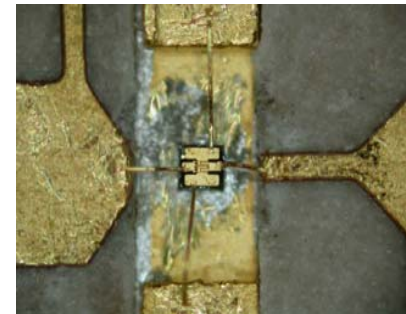
for $f \ll f_{\max}$

mHEMT-Performance at Cryogenic Temperatures

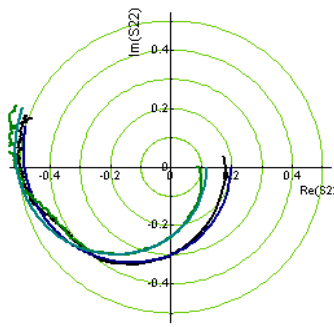
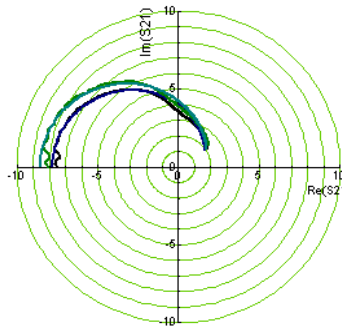
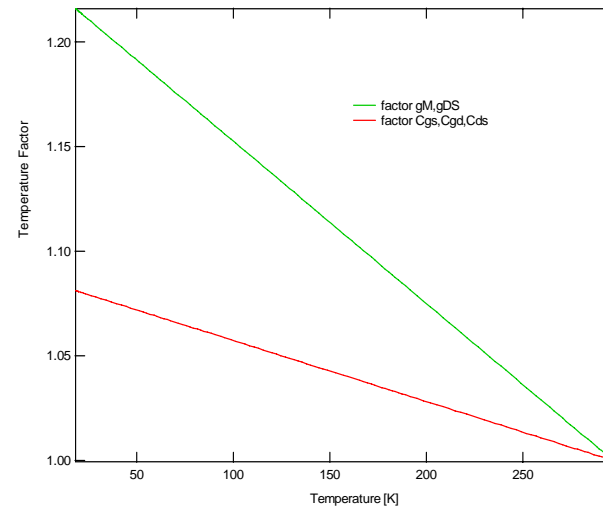
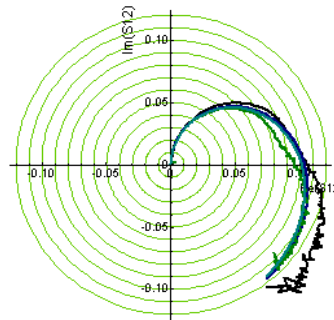
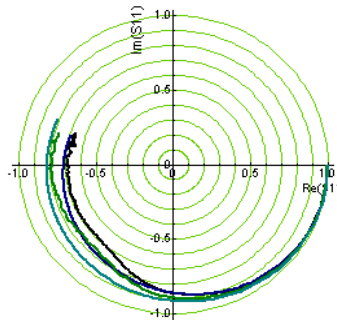


Test in Hybrid Amplifiers
 - First stage : 4x40 mHEMT
 - Gate Length 100 nm

Close to Best InP-HEMT performance
 $T_N \sim f/2$



Temperature Dependence S-Parameters

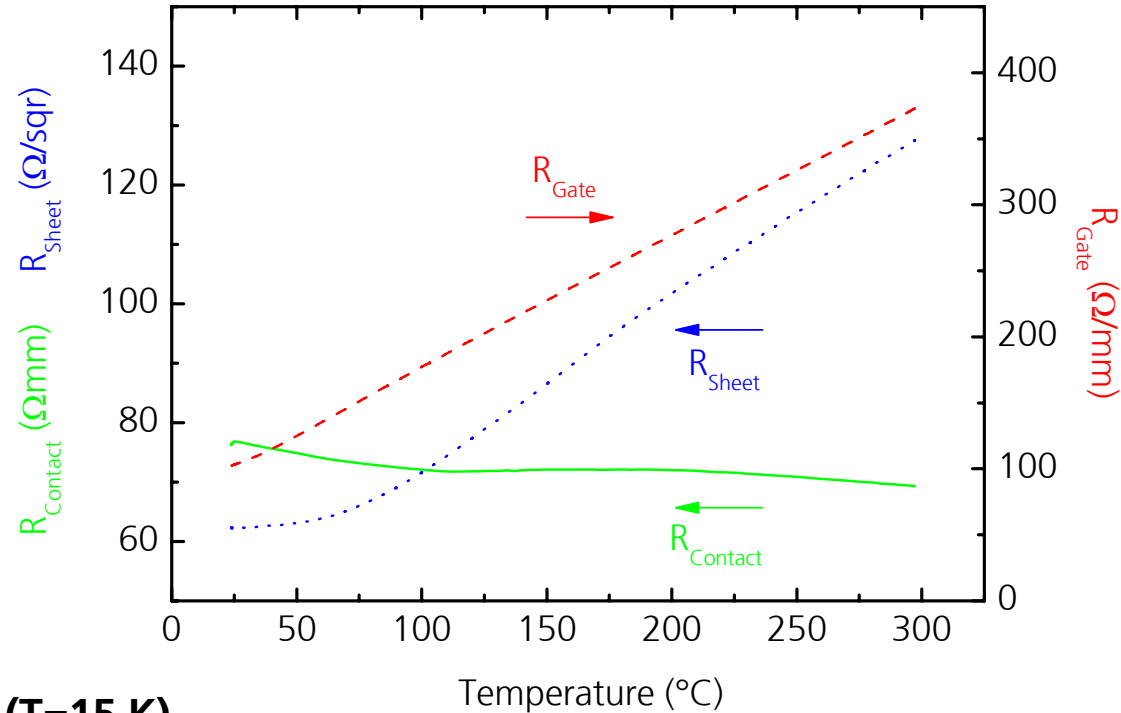
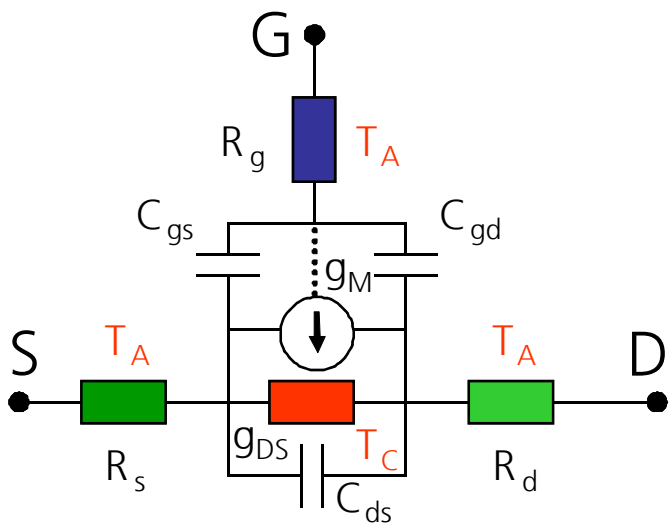


small signal elements:

- g_M, g_{DS} increase by 20% (v_{sat})
- C_{gs}, C_{gd}, C_{ds} increase by 8% (dielectric)



mHEMT Small Signal Model and T-Dependence of Noise Sources

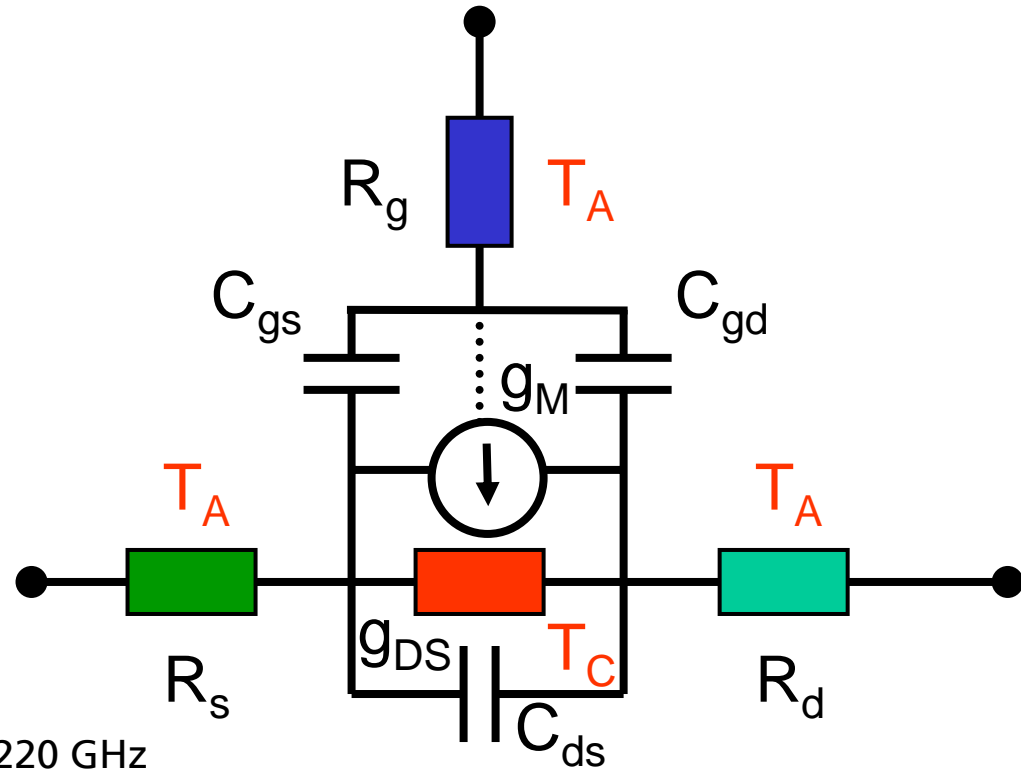
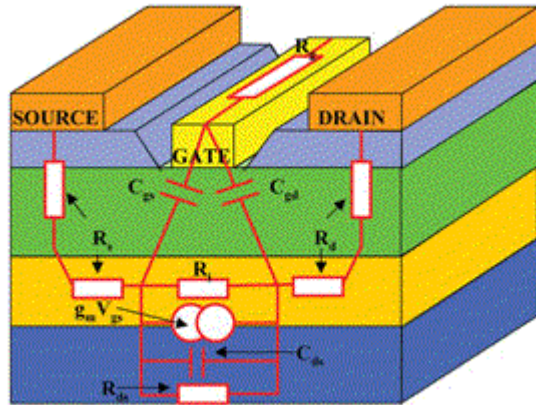


Changes RT-performance vs Cryo (T=15 K)

- R_{sheet} decreases (-55%)
- R_c increases (+10%)
- R_g decreases (-66%)



Extended IAF Lumped Element mHEMT-Model



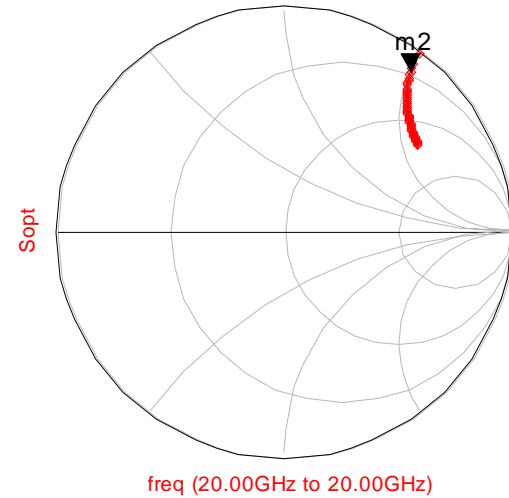
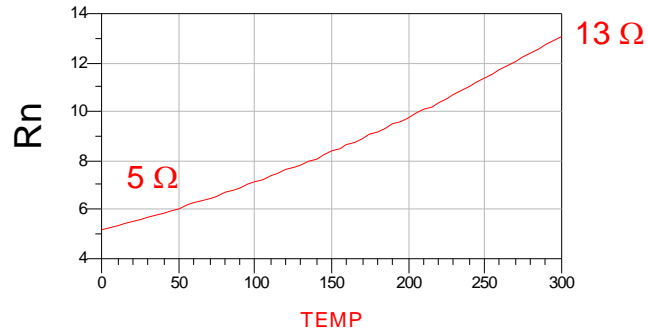
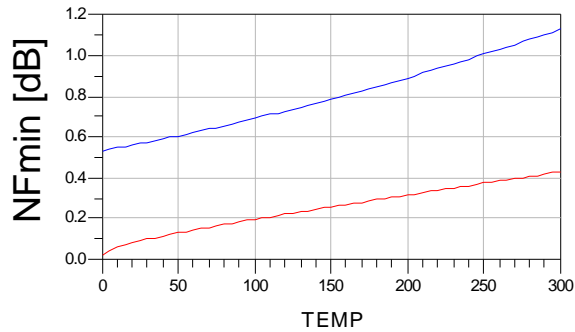
- ⇒ covers wide bias range
- ⇒ covers frequency range from 0.3 to 220 GHz
- ⇒ scalable from 10 μm to 120 μm
- ⇒ variable finger number
- ⇒ proper noise description
- ⇒ 15 K < T < 300 K

Assumptions Noise

- Noise Temperature R_s, R_d, R_g ambient
- Electron Temperature T_C not affected

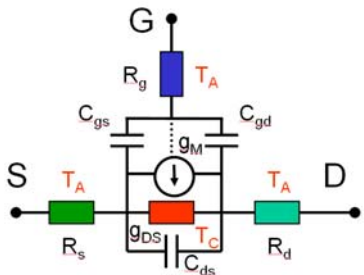
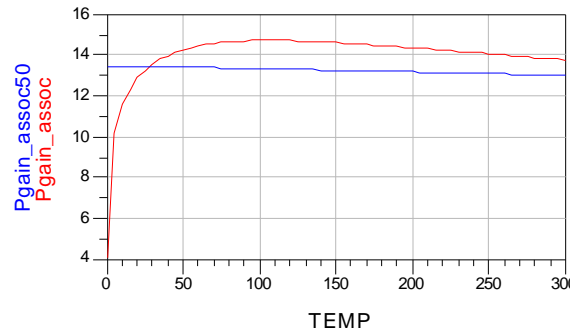
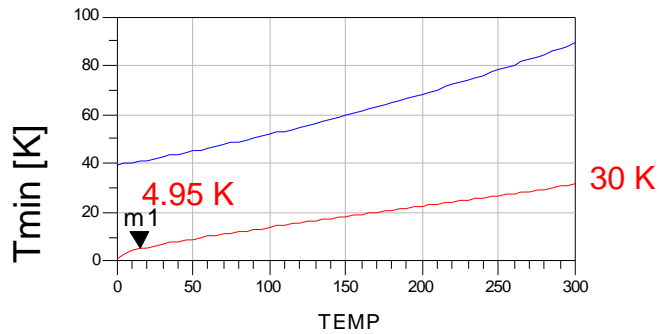
Model: Noise Performance vs. Temperature

F2x40: LG=50 nm; $i_d=150$ mA/mm; $V_d=1$ V; $f=20$ GHz



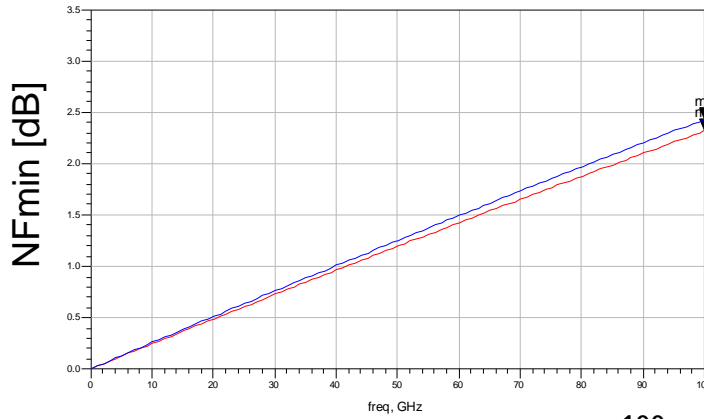
freq (20.00GHz to 20.00GHz)

m2
 freq=20.00GHz
 $S_{opt}=0.898 / 51.870$
 TEMP=15.000000
 impedance = $Z_0 * (0.278 + j2.026)$

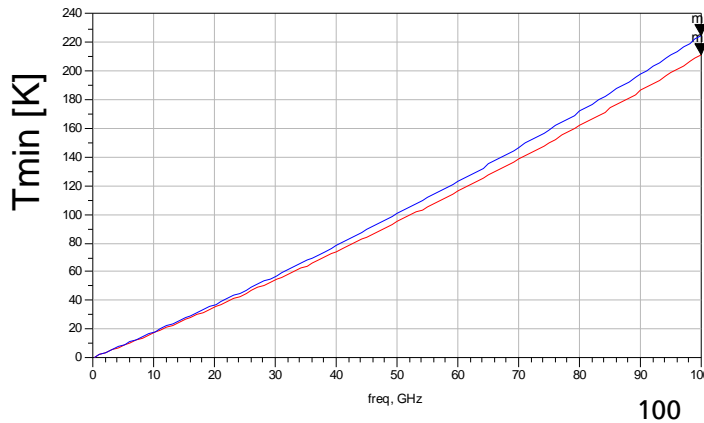


Influence of Output Conductance on Noise

F2x30
 LG=100 nm
 T=300K
 $i_D=150$ mA/mm
 $V_{ds}=1$ V

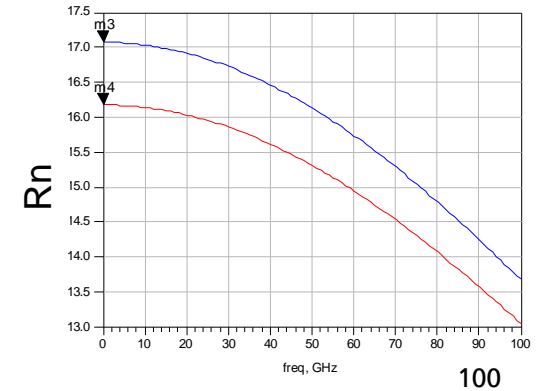
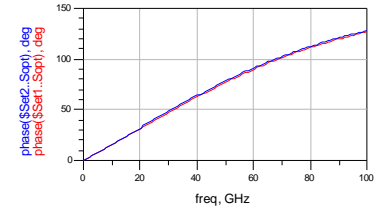
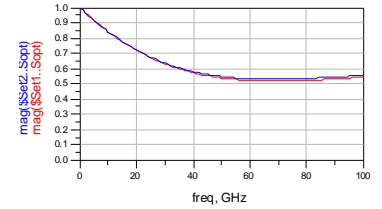
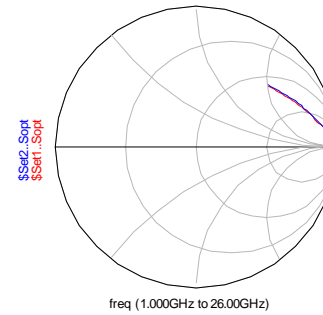


Freq[GHz] 2.317 | 17 | 2.430 | 30

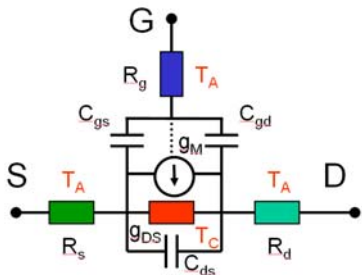


211 K | 224 K

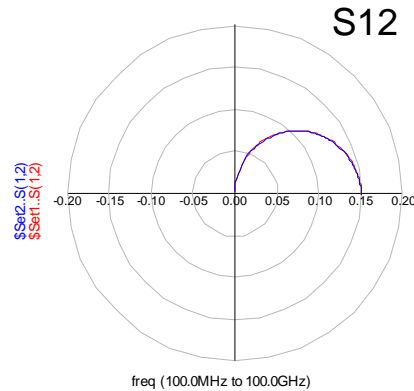
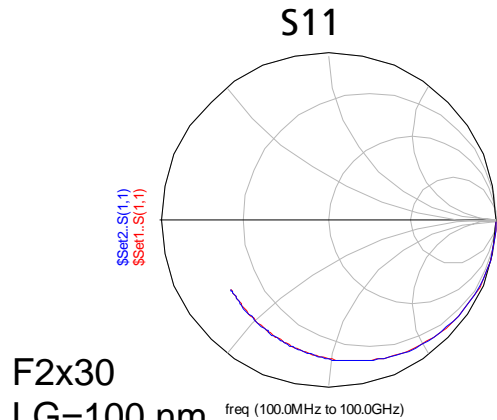
Sopt



16.18 | 17.07

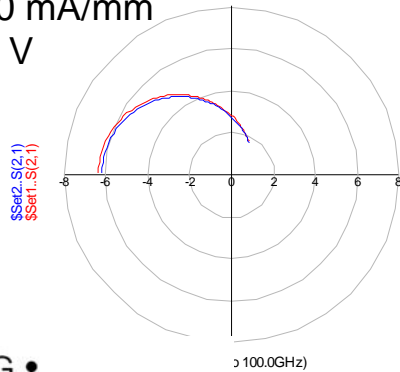


Influence of Output Cond. on SS-Performance

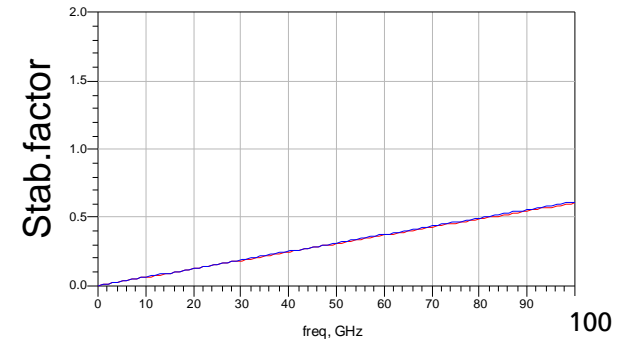
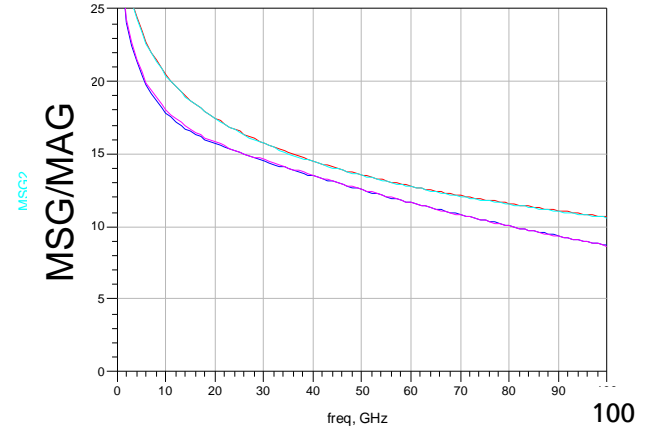
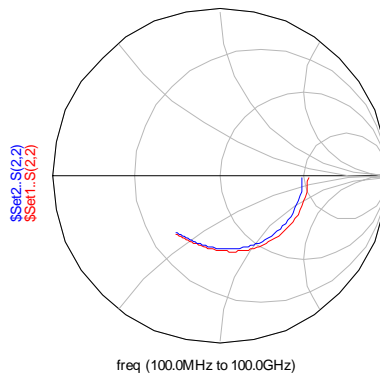


F2x30
 LG=100 nm
 T=300K
 $i_D=150$ mA/mm
 $V_{ds}=1$ V

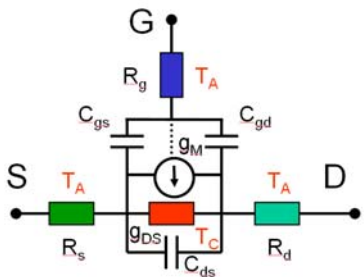
S21



S22



Red: model
 Blue: g_{DS} plus 10%
 $F_{min}:+5.0\%$; $R_n:+5.5\%$

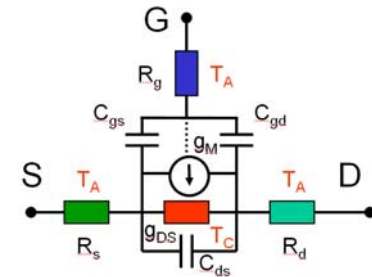


Technological Improvements?

Idea for Sensitivity Test:

- Increase Contribution of Noise Sources by 10%
- Use model to calculate noise parameters

	$\Delta NF_{min}[\%]$	$\Delta R_n[\%]$
R_g	+2.8	+2.2
R_s	+1.6	+2.6
R_d	+0.3	+0.0
g_{DS}	+4.9	+5.5



F2x30

LG=100 nm

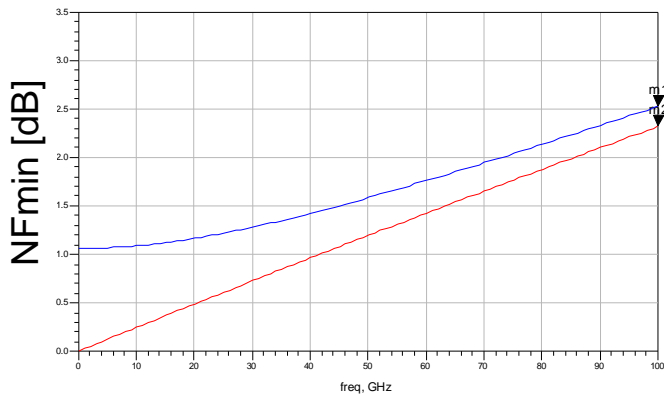
T=300K

$i_D=150$ mA/mm

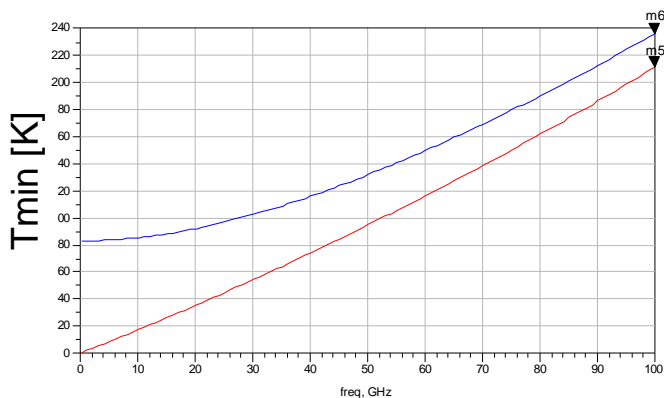
$V_{ds}=1$ V

Influence of Gate Leakage on Noise

F2x30
 LG=100 nm
 T=300K
 $i_D=150$ mA/mm
 $V_{ds}=1$ V

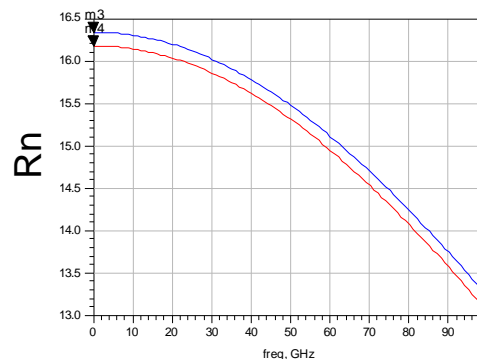
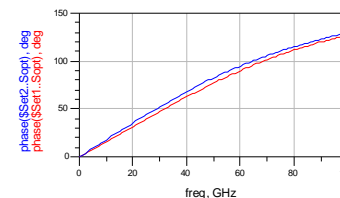
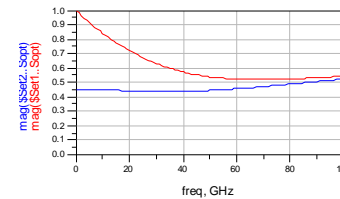
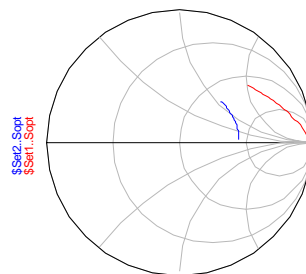


$\left[\begin{matrix} n \\ f \end{matrix} \right]_{\$} 2.317 \quad \left[\begin{matrix} n \\ f \end{matrix} \right]_{\$} 2.542$



211 K 236 K

Sopt

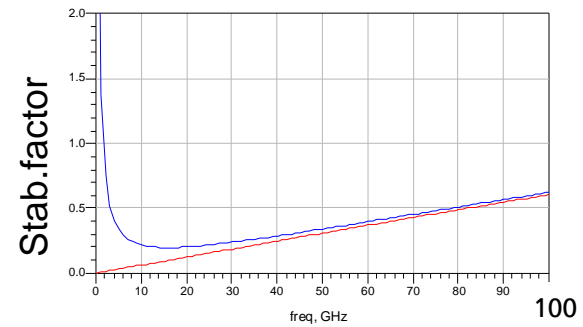
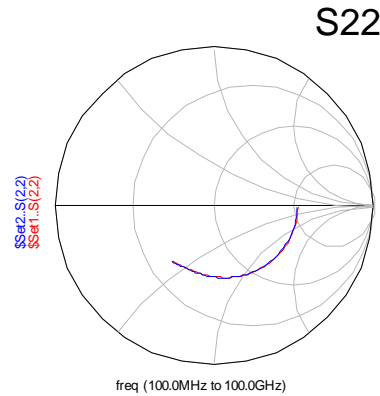
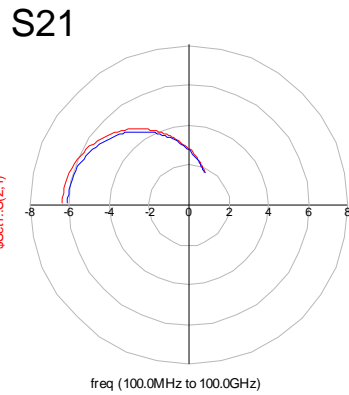
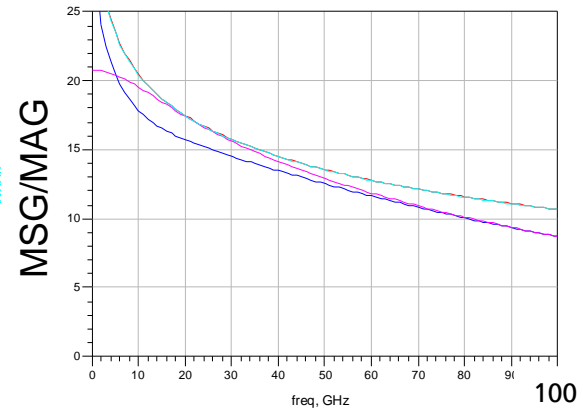
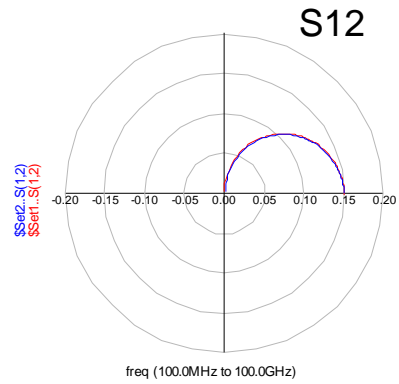
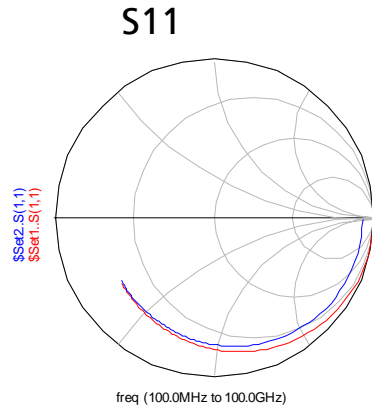


m4
 freq=100.0MHz
 SSet1...Rn=16.176

m3
 freq=100.0MHz
 SSet2...Rn=16.339

Gate Leakage : $g_{GS}=15$ m Ω /mm ($i_{GS}\approx 0.5$ mA/mm)

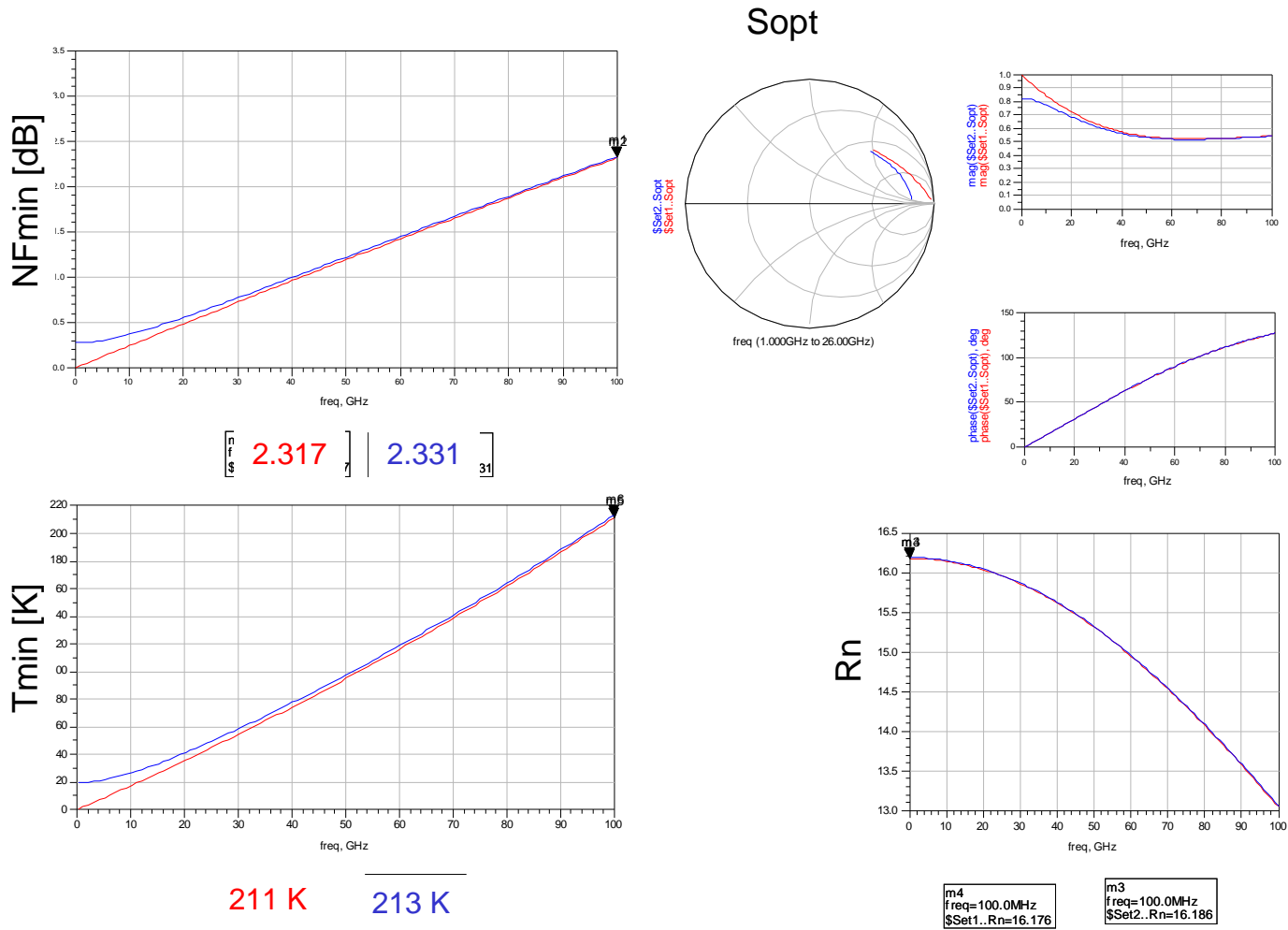
Influence of Gate Leakage on SS-Performance



F2x30
 LG=100 nm
 T=300K
 $i_D=150$ mA/mm
 $V_{ds}=1$ V

Gate Leakage : $g_{GS}=15$ m Ω /mm ($i_{GS}\approx 0.5$ mA/mm)

Influence of Gate Leakage on Noise

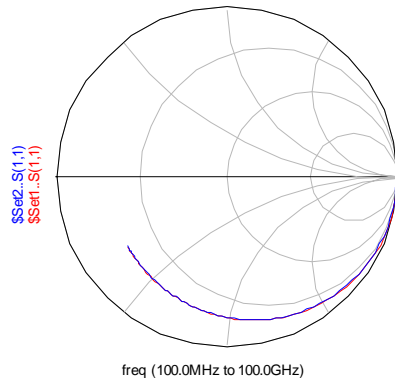


F2x30
 LG=100 nm
 T=300K
 $i_D=150$ mA/mm
 $V_{ds}=1$ V

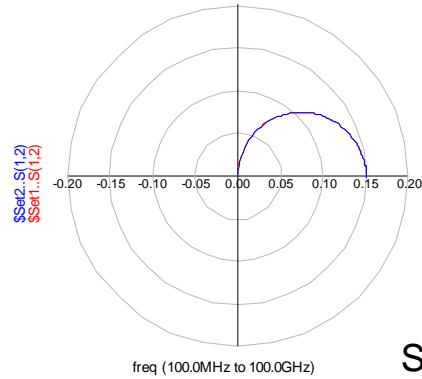
Gate Leakage : $g_{GS}=1$ m Ω /mm ($i_{GS}\approx 40$ μ A/mm)

Influence of Gate Leakage on SS-Performance

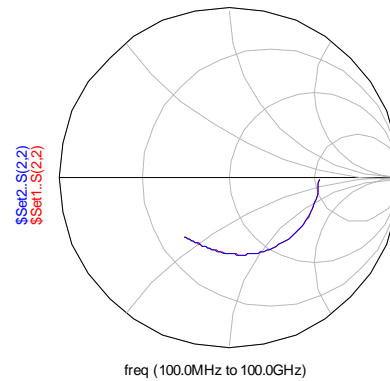
S11



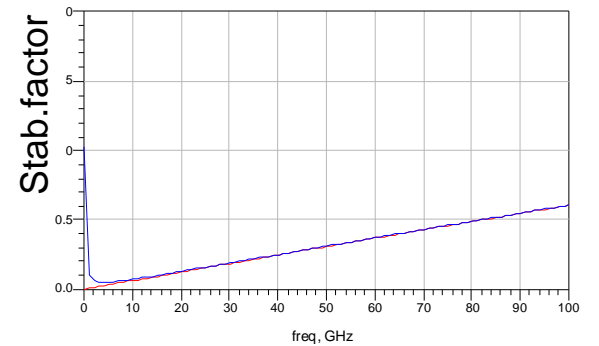
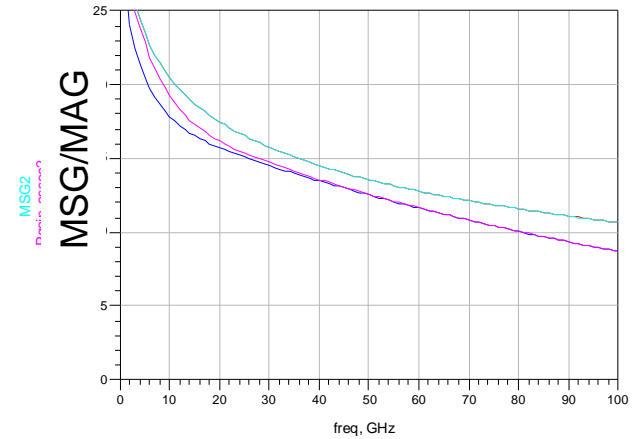
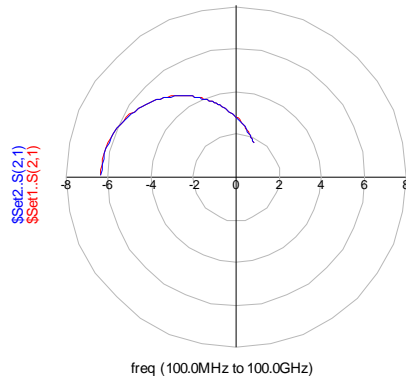
S12



S22



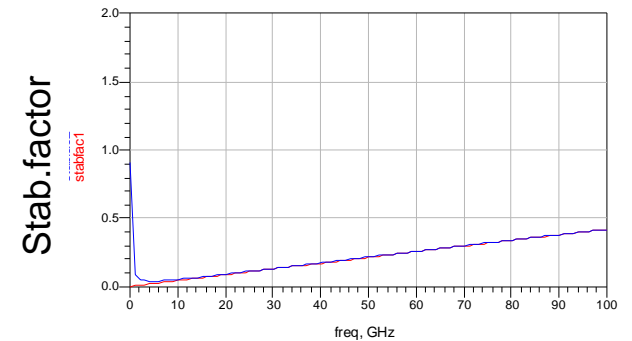
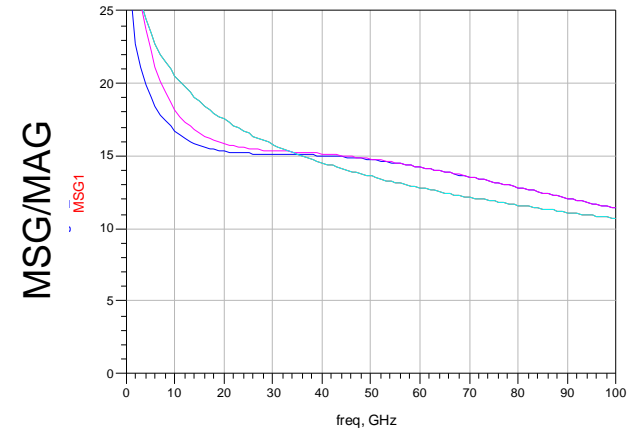
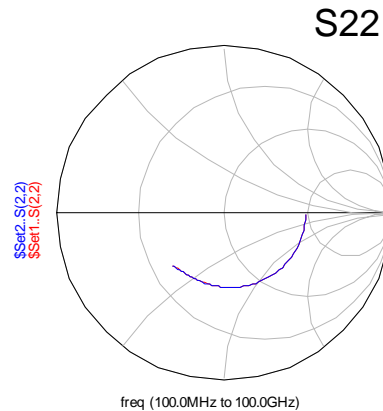
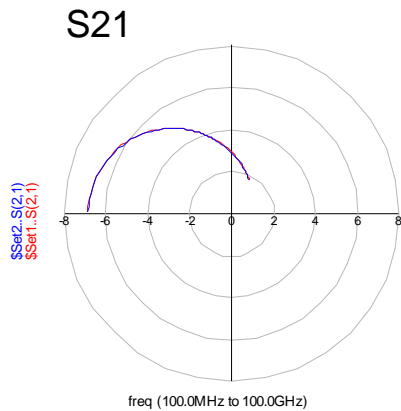
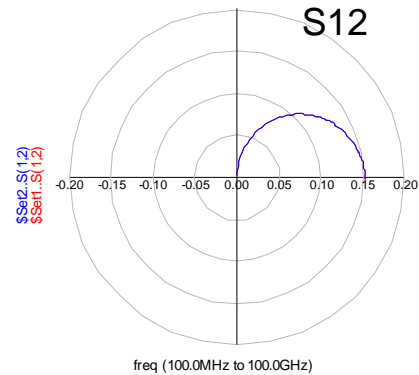
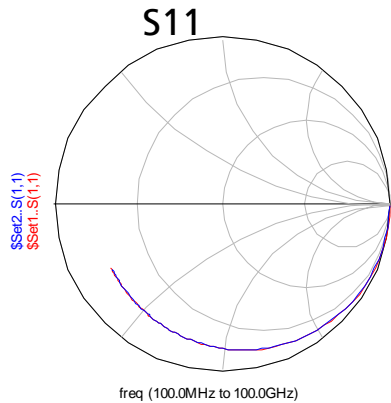
S21



F2x30
 LG=100 nm
 T=300K
 $i_D=150$ mA/mm
 $V_{ds}=1$ V

Gate Leakage : $g_{GS}=1$ m Ω /mm ($i_{GS}\approx 40$ μ A/mm)

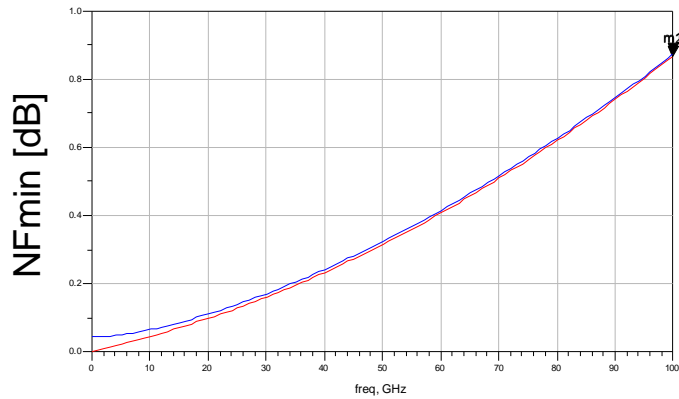
Influence of Gate Leakage on SS-Performance



F2x30
 LG=100 nm
 T=15K
 $i_D=150$ mA/mm
 $V_{ds}=1$ V

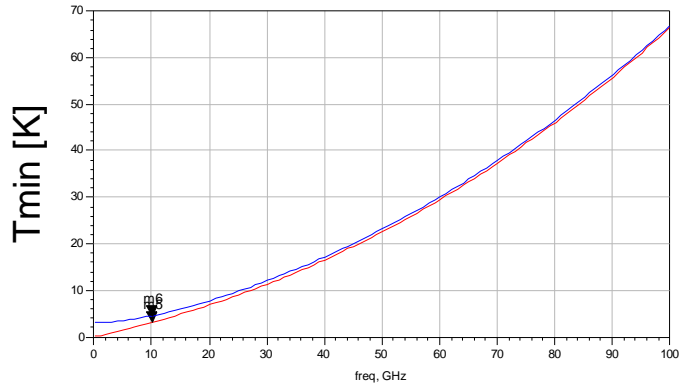
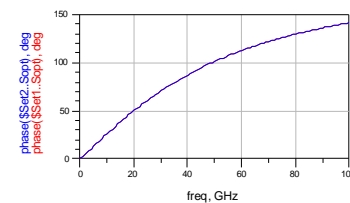
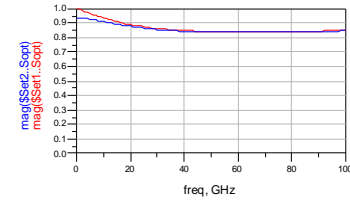
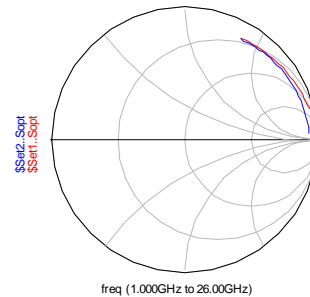
Gate Leakage : $g_{GS}=1$ m Ω /mm ($i_{GS}\approx 0.5$ mA/mm)

Influence of Gate Leakage on Noise

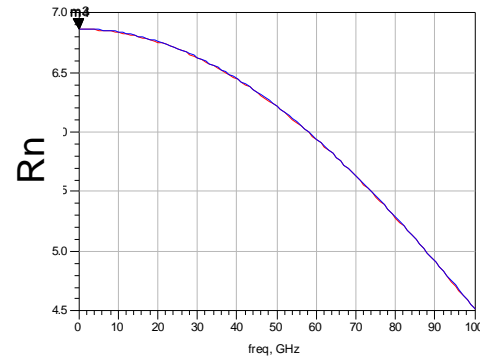


0.867 67 0.873 3

Sopt



3.13 K 4.53 K



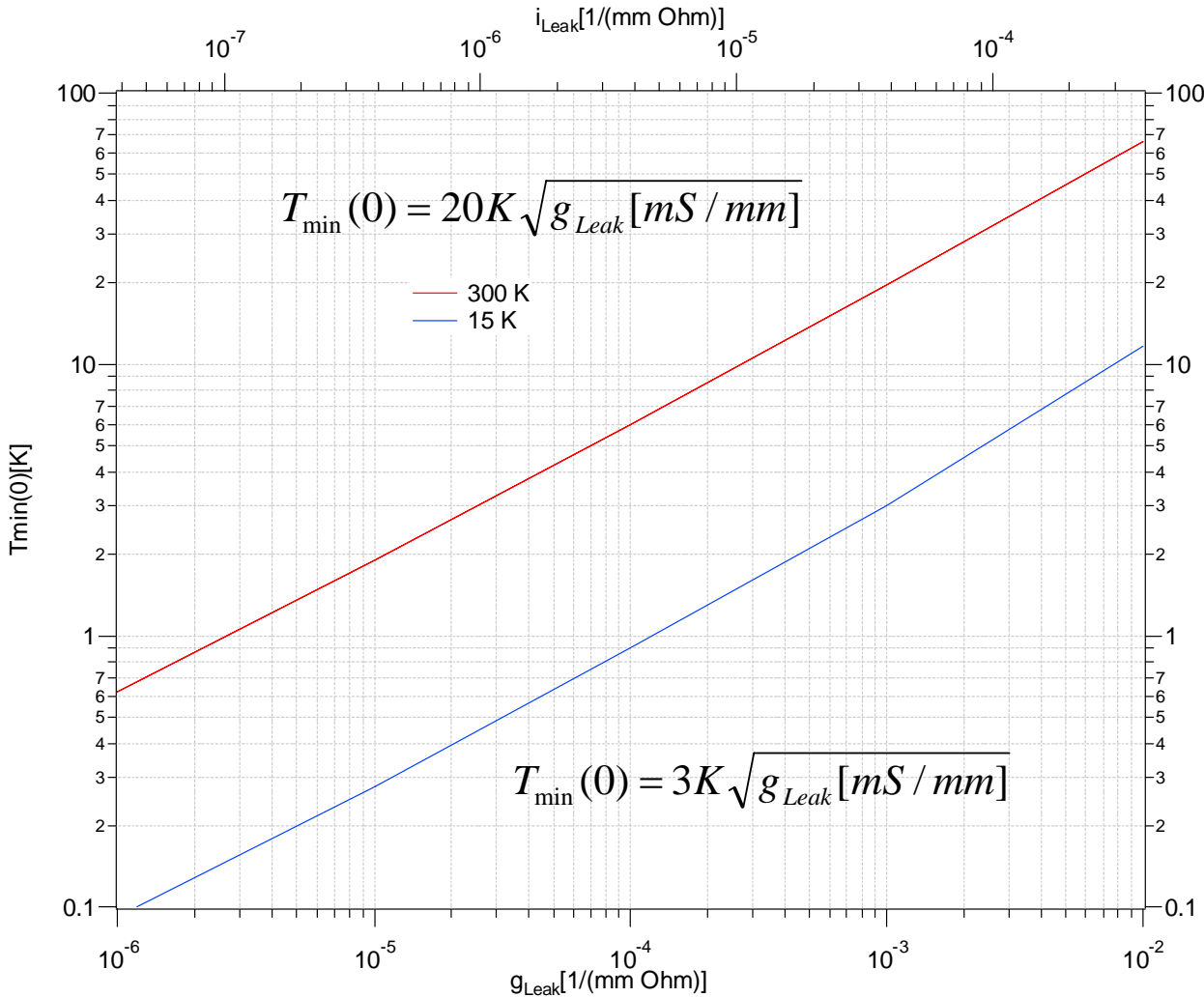
m4
freq=100.0MHz
\$Set1..Rn=6.862

m3
freq=100.0MHz
\$Set2..Rn=6.866

F2x30
LG=100 nm
T=15K
 $i_D=150$ mA/mm
 $V_{ds}=1$ V

Gate Leakage : $g_{GS}=1$ m Ω /mm ($i_{GS}\approx 40$ μ A/mm)

T_{\min} with Gate-Leakage



Similar effect for g_{GS} and g_{GD}

F2x30(LG=100)

Conclusions

- Scalable/bias-dependent cryo-model
 - Large temperature variations for access resistances
 - Slight increase of intrinsic conductances/capacitiies
- Gate Leakage
 - affects T_{Nmin} and S_{opt}
 - critical for C- and X-band LNAs
 - Little effect in W-band
- Potential for Cryo-Optimization ?
 - Large Decrease of R_g, R_s, g_{DS} necessary to achieve small decrease in T_{min}
 - R_d can be significantly increased without noise deterioration